

Measurement of Nanometer Electron Beam Sizes with Laser Interference using IPBSM

IBIC2012

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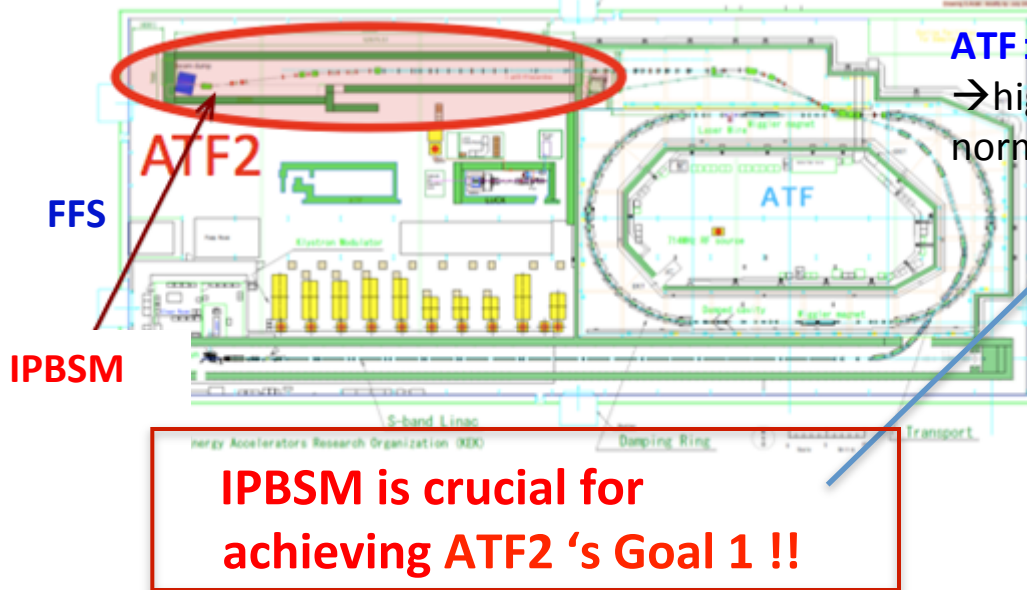
Role of IPBSM (Shintake Monitor) at ATF2

ATF2: Linear Collider FFS test facility@KEK

$$L = \frac{n_b N^2 f_{rep}}{4\pi\sigma_x \sigma_y} H_D$$

For high luminosity
**must focus
vertical beam size at IP !!**

flat beam : $\sigma_y \ll \sigma_x$



ATF: 1.28 GeV LINAC , DR

→ high quality e- beam with extremely small normalized vertical emittance $\gamma\epsilon_y$

ATF2 Goal 1 :

focus σ_y^* to design size **37 nm**

→ verify Local Chromaticity Correction

ATF2 Goal 2:

O(nm) beam trajectory stabilization

OUTLINE

measurement scheme, performance, beam tuning roles

**Beam Time results
2011~2012**

upgrades

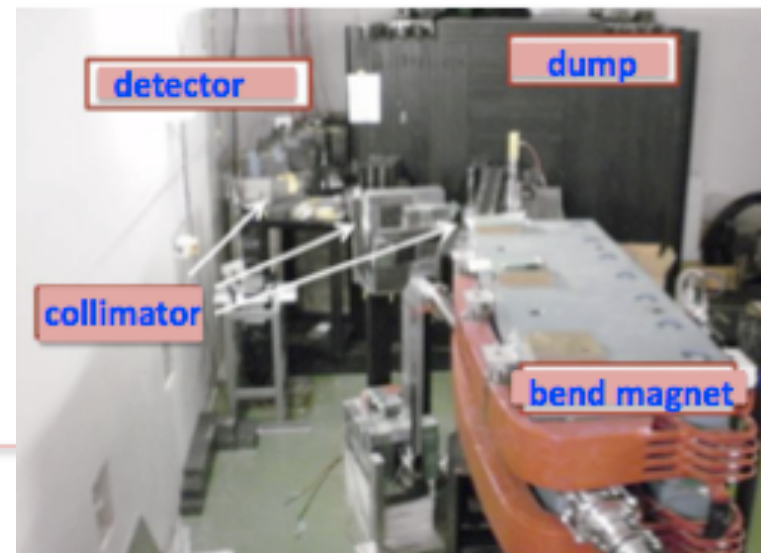
Summary & Goals

Measurement Scheme

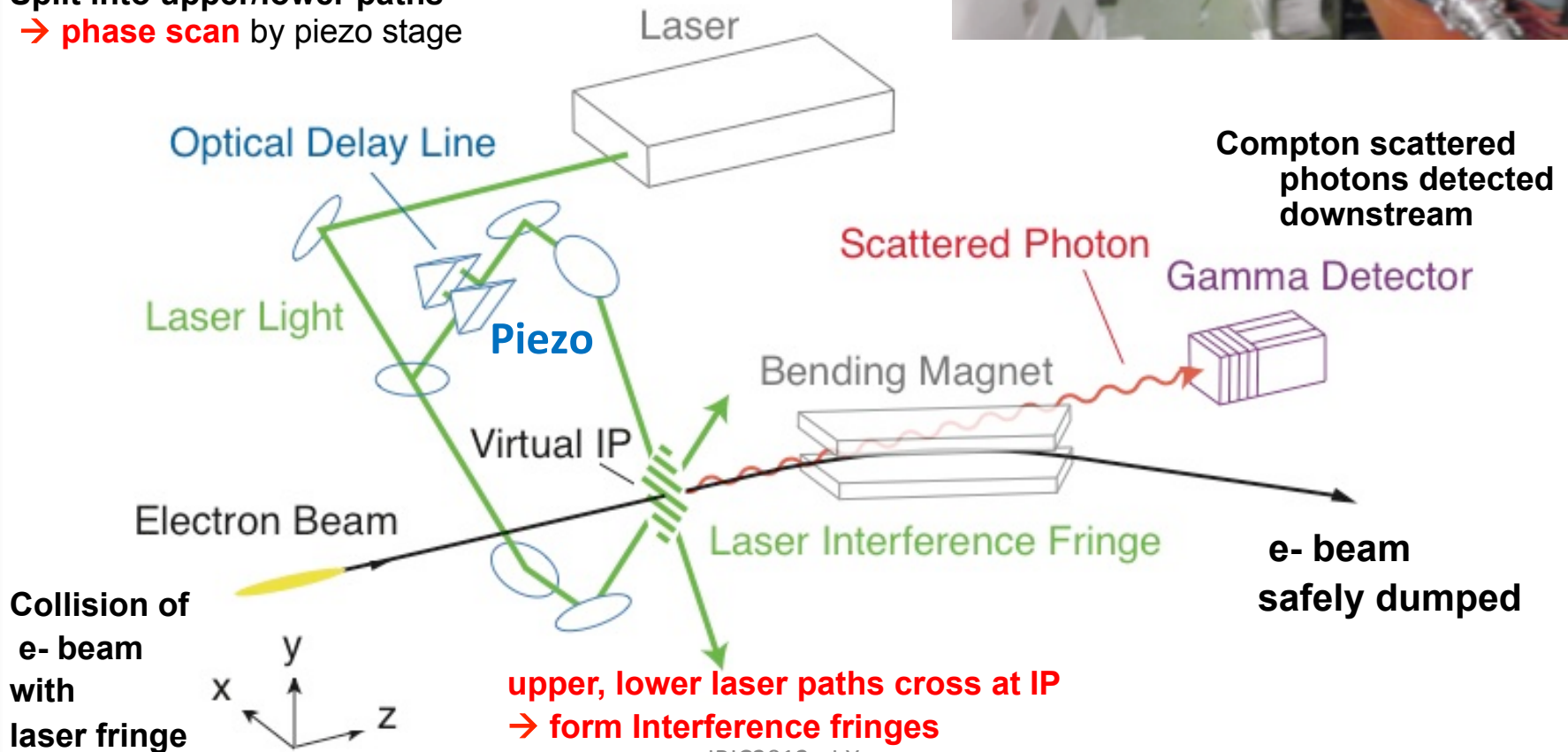
use **laser interference fringes** as target for e- beam

Only device able to measure $\sigma_y < 100$ nm !!

- Crucial for beam tuning
→ *realization of future linear colliders*



Split into upper/lower paths
→ **phase scan** by piezo stage



Detector measures
signal **Modulation Depth “M”**

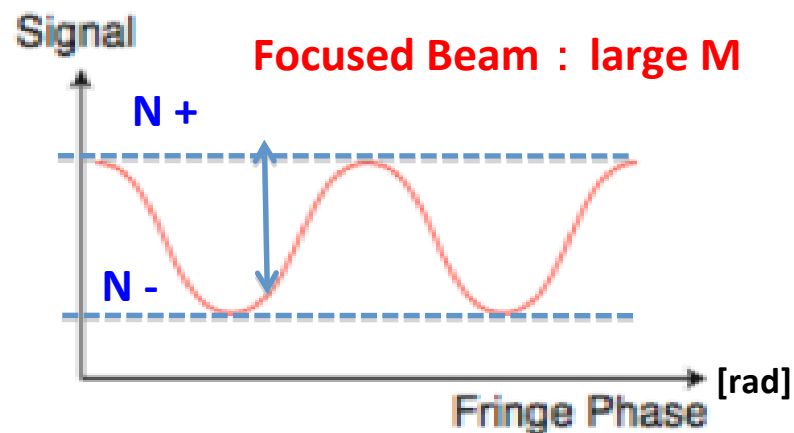
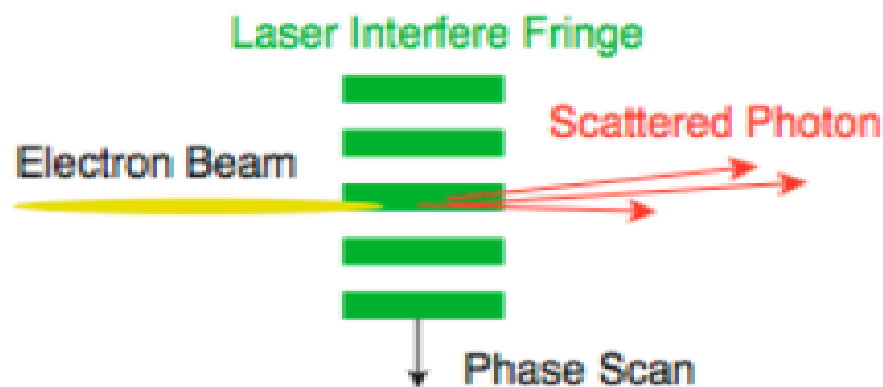
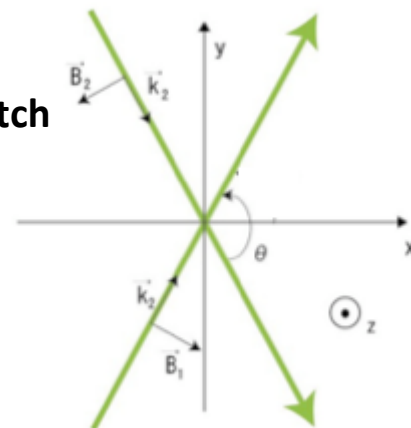
$$M = \frac{N_+ - N_-}{N_+ + N_-} = \left| \cos(\theta) \exp(-2(k_y \sigma_y)^2) \right|$$

$$\Rightarrow \sigma_y = \frac{d}{2\pi} \sqrt{2 \ln \left(\frac{|\cos(\theta)|}{M} \right)}$$

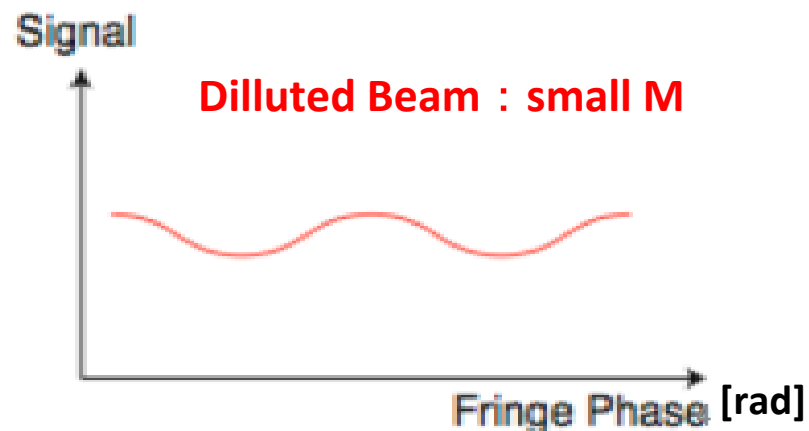
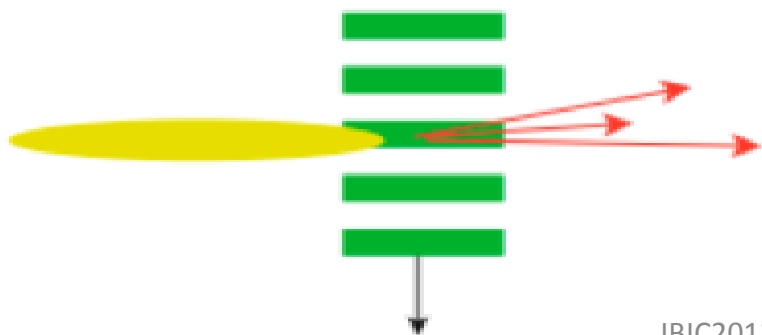
measurable range
determined by **fringe pitch**

$$d = \frac{\pi}{k_y} = \frac{\lambda}{2 \sin(\theta/2)}$$

depend on
crossing angle θ (and λ)



N: no. of Compton photons
Convolution between e- beam profile and fringe intensity



Crossing angle θ	174°	30°	8°	2°
Fringe pitch $d = \frac{\pi}{k_y} = \frac{\lambda}{2 \sin(\theta/2)}$	266 nm	1.03 μm	3.81 μm	15.2 μm
Lower limit	20 nm	80 nm	350 nm	1.2 μm
Upper limit	110 nm	400 nm	1.4 μm	6 μm

Expected Performance

$$37 \pm 2 \text{ (stat.) } {}^{-0}_{+4} \text{ (syst.) nm}$$

Measures

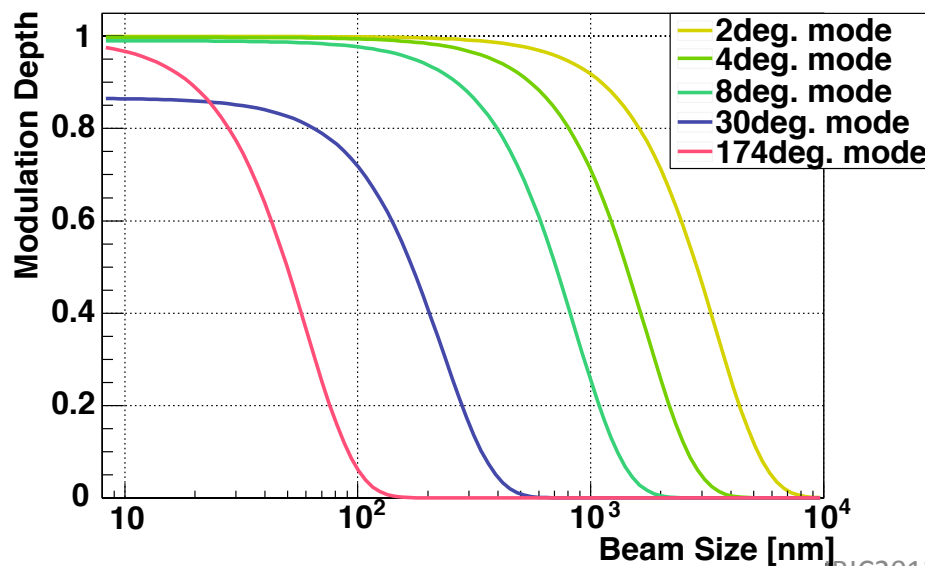
$\sigma_y^* = 20 \text{ nm} \sim \text{few } \mu\text{m}$
with < 10% resolution

$$\sigma_y = \frac{d}{2\pi} \sqrt{2 \ln \left(\frac{|\cos(\theta)|}{M} \right)}$$

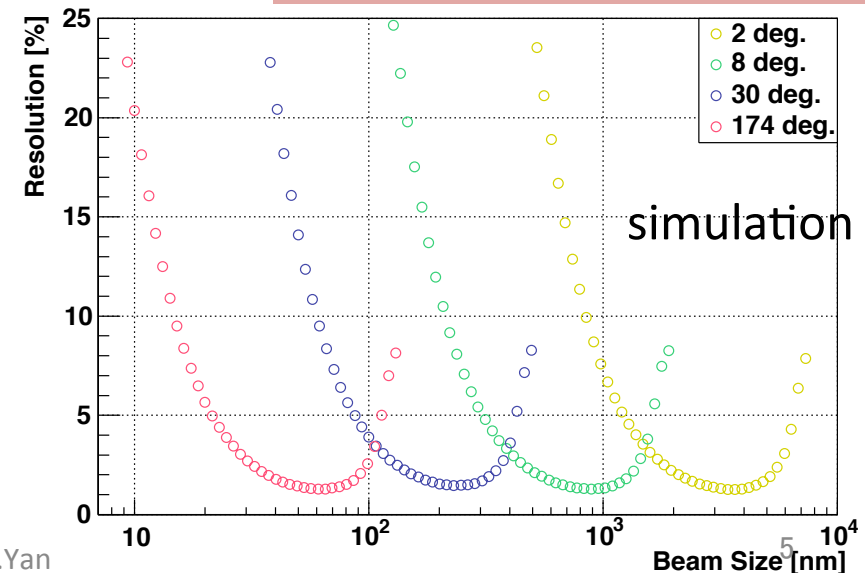
σ_y^* and M for each θ mode

must select appropriate mode
according to beam focusing

Resolution for each θ mode



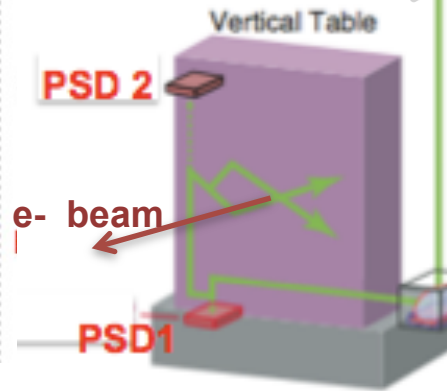
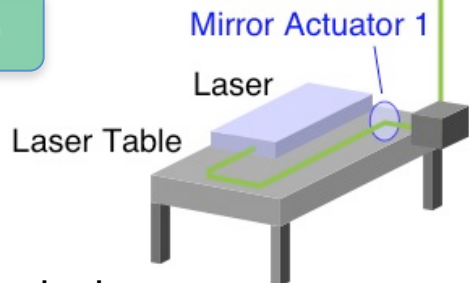
IBIC2012, J.Yan



Laser Optics

Laser table

- Source (SHG)
- diagnostic devices



Vertical table

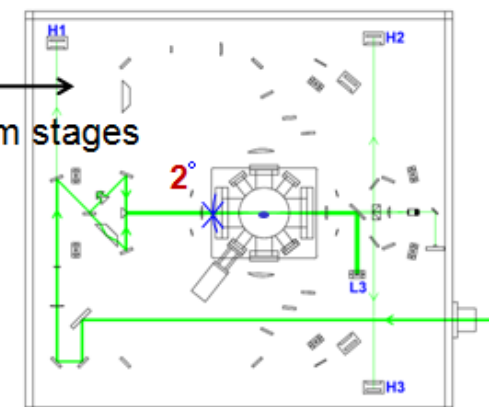
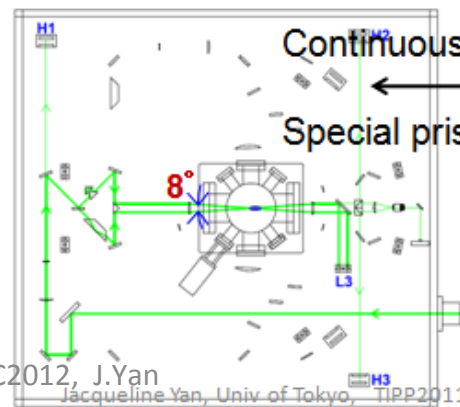
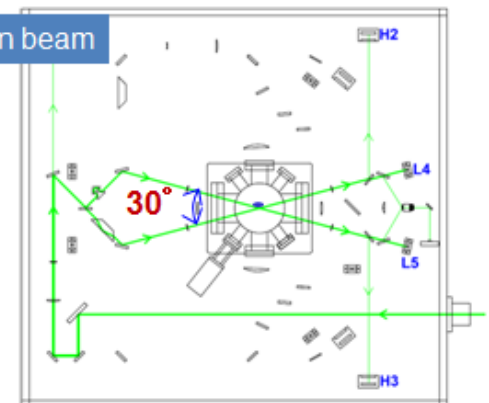
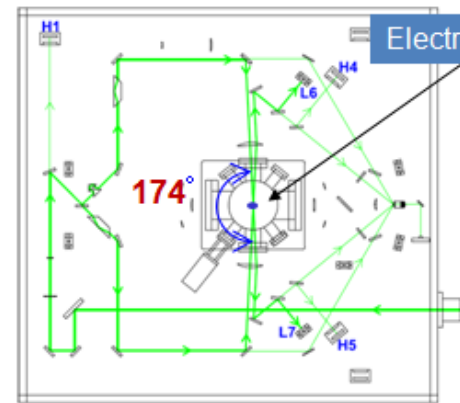
Interferometer

- Phase control
→ piezo stage
- construct path for each θ mode
(auto-stage + mirror actuators)

**Nd :YAG
Q-Switch laser**

PRO350
Spectra Physics

Wavelength	532 nm (SHG)
Pulse Energy	1.4 J
Peak power	164 MW
Pulse Width	8 ns (FWHM)
f_{rep}	6.25 Hz
Line Width	$< 0.003 \text{ cm}^{-1}$
Timing Stability	$< 0.5 \text{ ns}$
Energy Stability	$\pm 3\%$



Continuous
Special prism stages



X and Y
actuators



Rotation stage

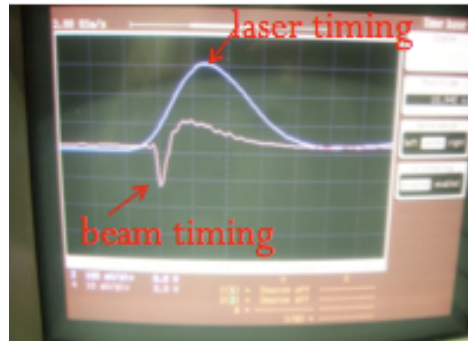
Role of IPBSM in Beam Tuning

1 path construction: access to IP, confirm precision with “ eyes & hands”

switch e- beam ON → remote control

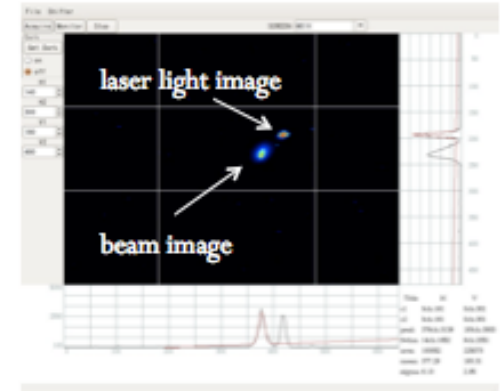
2 Timing alignment

Timing scan of laser Q-SW and e- beam
→ matched with precise TD2



3 Preliminary position alignment

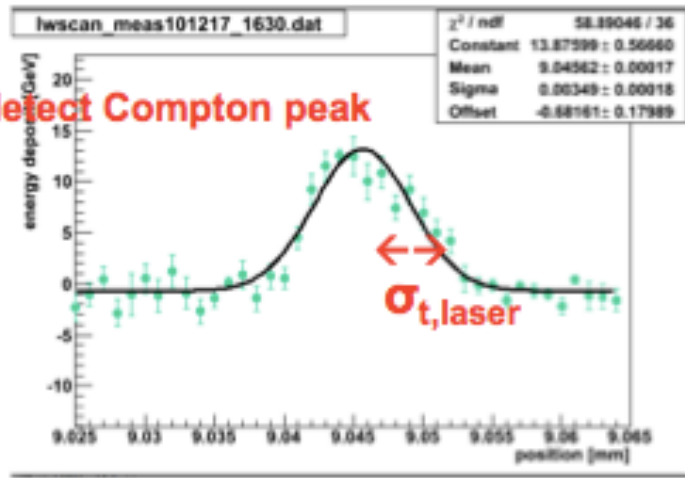
Overlap laser and e- beam spots on screen monitor
(within $\sim 20 \mu\text{m}$)



extremely precise position alignment

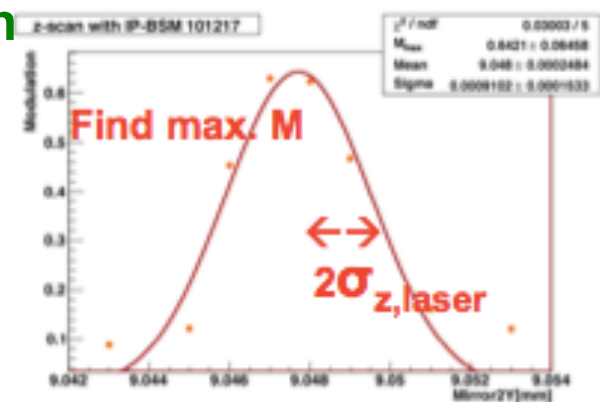
4 transverse : defect Compton peak

laser wire scan



5 Longitudinal:

z scan



6 After all preparations

continuously measure σ_y^* using interference mode
→ Feed back to beam tuning

post-earthquake recovery and upgrade in 2011

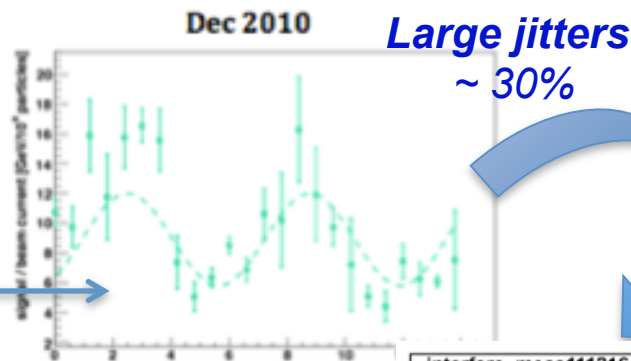
- overall stabilization of laser optics
- suppress signal jitters

Beam Time (autumn~)

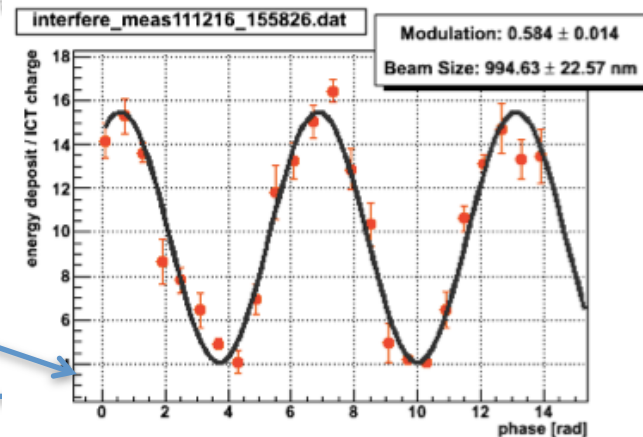
σ_y^* focused down to $\sim 1 \mu\text{m}$
(beam tuning issues)

IPBSM resolution improved
(2 – 8 deg mode)

much smaller jitters
clear contrast



Hardware upgrade



overcome signal jitter sources (example)

Beam size jitter

high response , effective
status monitors
& scan software
introduced to ATF2

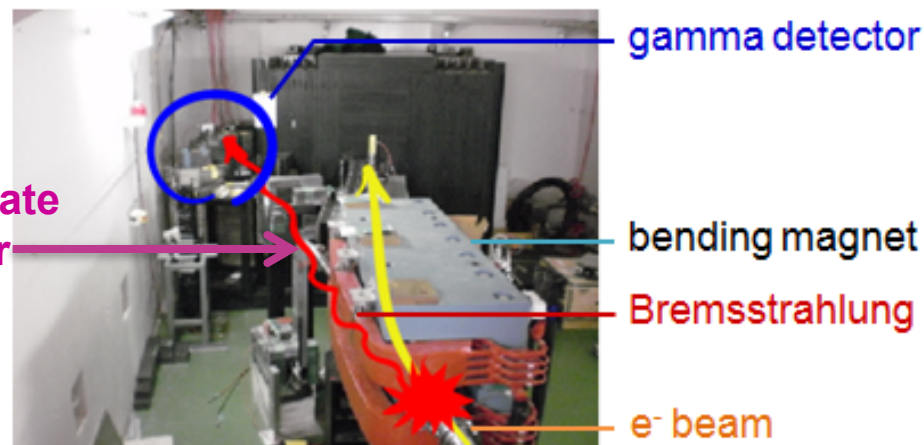
➔ monitor instability factors
on beam/laser profile

High BG

intermediate
collimator
installed

fast M detection → scan under stable conditions

extra bremsstrahlung at post-IP dipole



Beam time status in 2012

**full commissioning
of 30° mode**

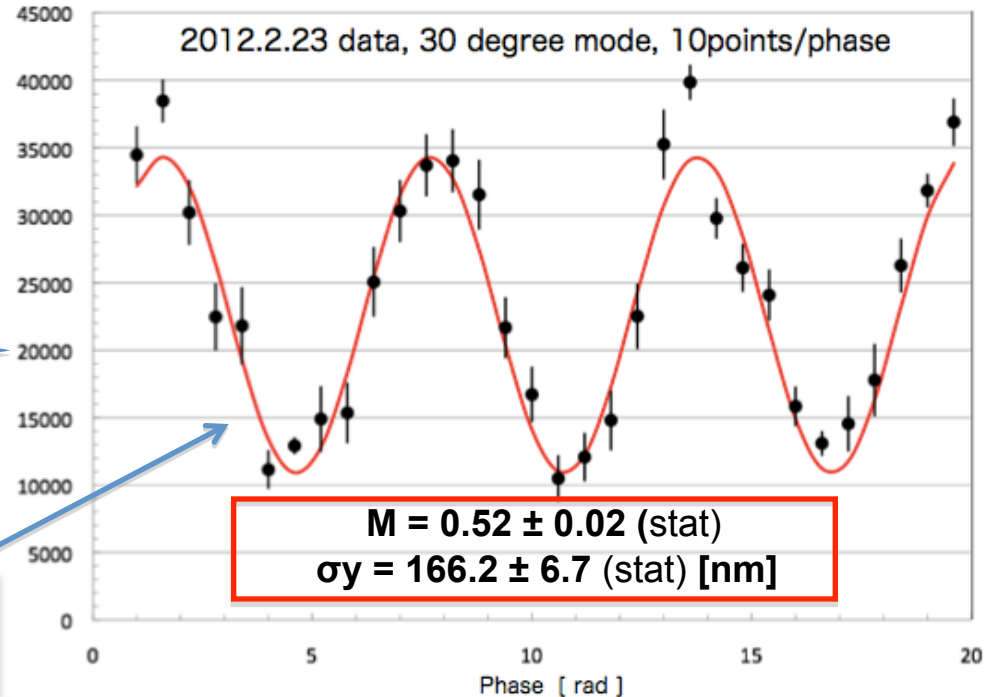
First Modulation detection

($10 \times \beta_x^*$, $10 \times \beta_y^*$ optics)

stably measure $\sigma_y^* \sim 160$ nm

($10 \times \beta_x^*$, $3 \times \beta_y^*$ optics)

Signal Energy / ICT intensity [arb. unit]



2 - 8 ° mode

Measured larger σ_y ($\sim$ few 100 nm)
with clear **contrast**

(i.e. high M : 0.8 – 0.9)

- ➔ **Syst error study**
- ✓ **upper limit on M_{meas}**
- ✓ **consistency of $\sigma_{y\text{-meas}}$**

Began commissioning of 174 ° mode

- **hardware check**
- **Optimization of scan strategies**

Obstacles (2012 Feb)

- Beam condition drift (over many hours)
- Not very focused σ_y^* (still at $3 \times \beta_y^*$ optics)

**one more step before full commissioning of
174 ° mode i.e. consistent fringe scans**

Systematic Error Study

Interpretation of
M under-evaluation / σ_y^* over-evaluation)

Modulation Reduction Factor

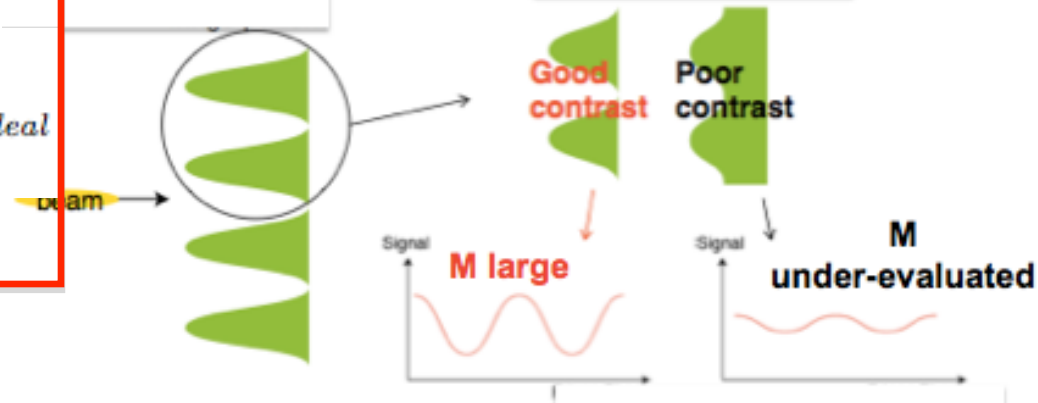
$$M_{meas} = C_1 C_2 \dots M_{ideal} = \left(\prod_i C_i \right) M_{ideal}$$

$$\sigma_{y,ideal}^2 + \frac{1}{2k_y^2} \left| \sum \ln C_i \right|$$

Example of syst error evaluation

(June, 2012 ,4 mode)

degraded fringe contrast due to bias



major
bias
factors

Laser profile imbalance

compare Compton signal
of upper / lower path laser wire scans

Fringe tilt

limited by alignment precision

Phase jitter (relative position)

$C_{phase} > 95\%$

Laser path alignment

$C_{t,pos} : \sim 100\%$, $C_{z,pos} : > 99.5\%$

*M reduction
"worst limit"*

polarization

$> 98\%$ adjusted to nearly pure S state

From actual data:

upper limit on M (= "fringe contrast")

$C_{total} = 0.8 - 0.9$

Dominant Systematic Errors (2012 continuous run)

Improve through 2012 summer upgrade

Profile Imbalance

- ✓ peak power
- ✓ IP spot size σ_{laser}

◆ partially: optical components related loss
(transmission, reflection, delay line
total $P_l = 0.88$)

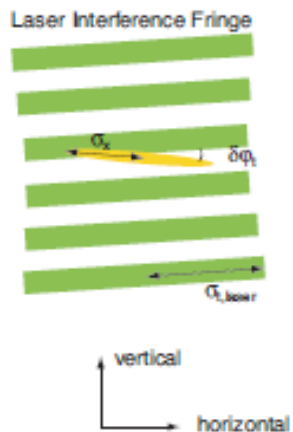
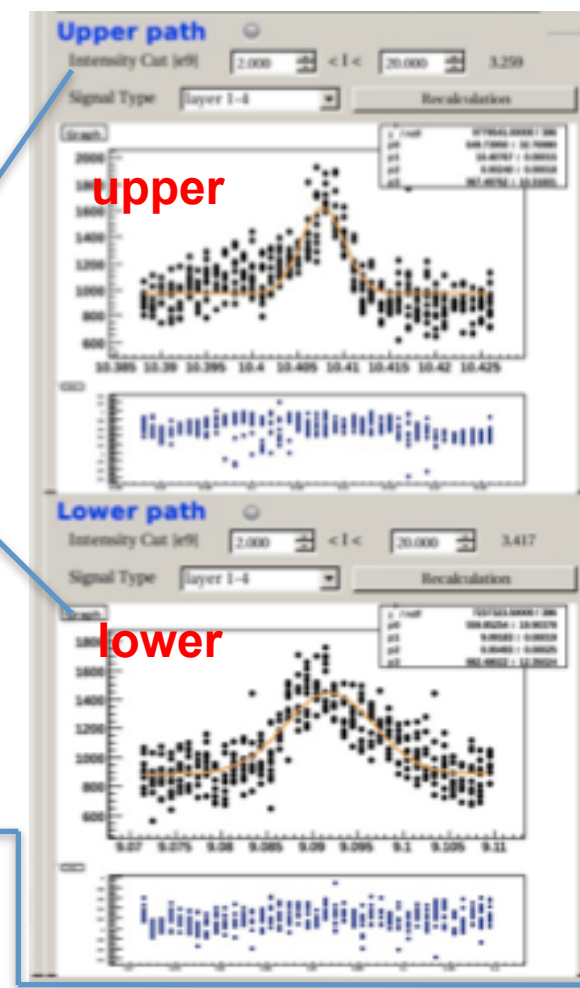
◆ lens misalignment

→ Difference in focal point position

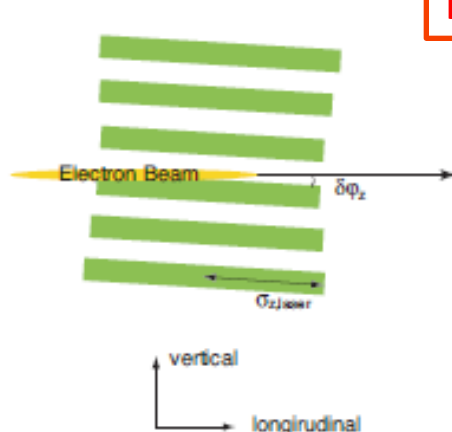
2 times difference in
laser-wire
Compton signals ($N_{\text{av}} = 20$)

$$M' = CM = \frac{2\sqrt{P_l}}{1 + P_l} M$$

$$P_l = P_U / P_D$$



transverse



longitudinal

Fringe Tilt

fringe not formed
perpendicular
to e- beam axis

→ improve alignment precision
on final focus lens before IP

observable limit: $\Delta = 3 - 5 \text{ mm}$

↔ tilt $\delta\phi_{t,z} : 5 - 20 \text{ mrad}$

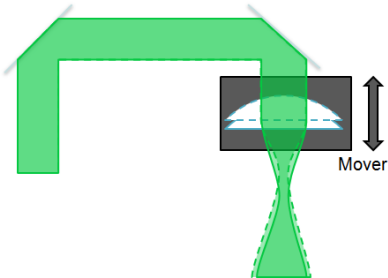
Syst. Errors specific to very small σ_y^* (174 deg mode)

Spherical wavefronts

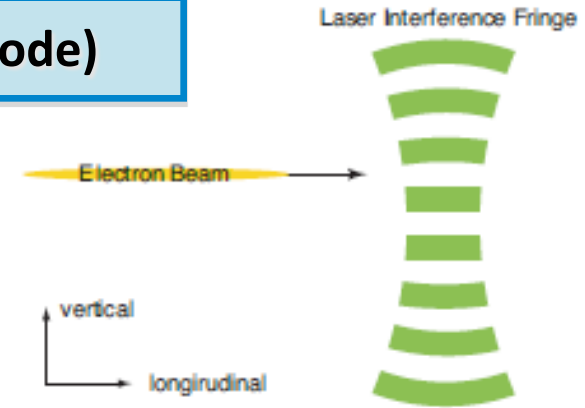
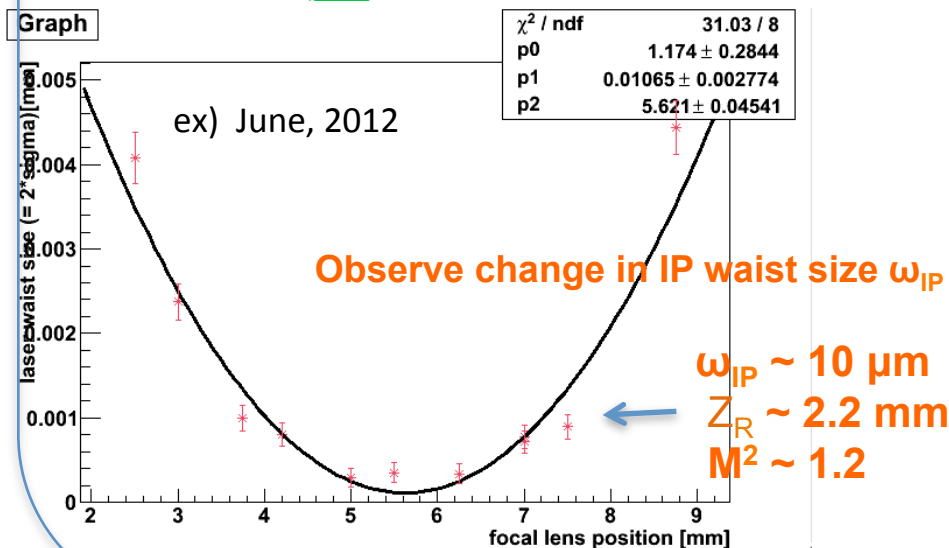
Offset of ultra-focused
e- beam vs laser waist

→ distorted fringes
 $C_{\text{sphere}} > 99.7\%$

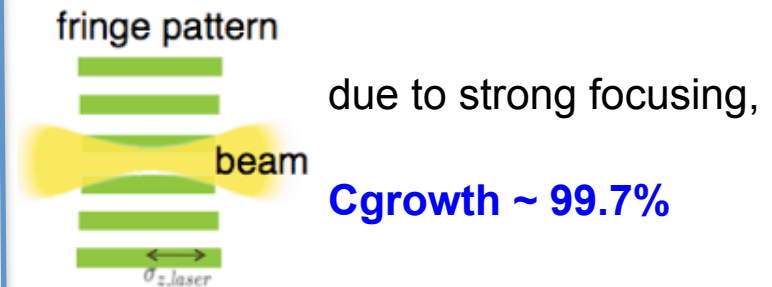
Solution is **focal point scan**



attach mover to lens
→ align focal point to IP
within $< 100\ \mu\text{m}$
($\sim 0.1 \times \text{Rayleigh length } Z_R$)



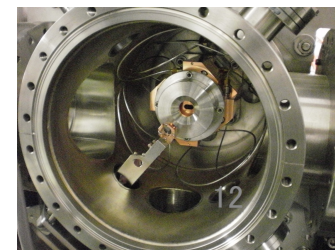
Change of σ_y^* within fringes



Tiny σ_y^* is very sensitive to
relative position jitter !!

IPBPM (O(nm) design resolution)
under commissioning

- beam pos. monitoring
- feedback correction



2012 summer: **major upgrade of laser optics**

Goal: **alignment precision & reproducibility**

- suppress syst. errors
- effective small σ_y^* tuning
- better conditions to accomplish goals in autumn beam run

BEAM TIME GOAL:

- ◆ Full commissioning of 174° mode
 - stably measure $\sigma_y^* < 100$ nm
 - focus down to $\sigma_y^* \sim 37$ nm

improvements	details
easier alignment match focal point to IP Injection position / angle into lens	• focal point scan for all modes • redefine clear reference lines on new base plates
consistency , reproducibility esp. before / after mode switching	• new θ switching method {small linear stage + mirror actuators } independent for each mode (instead of shared rotating stages) • re-commission PSD system → monitor jitters / drifts
profile imbalance focal point difference between upper/lower paths	• suppress path length difference in new design

**Small linear stage
+ mirror actuator**

just after injection onto vertical table

Firm lens holders

**Confirm fine alignment using
CW laser and transparent IP target**

**check positioning
of lens, mirror, prism**

inside IP
chamber
→ laser waist
&
crossing point

prism

CW laser spot

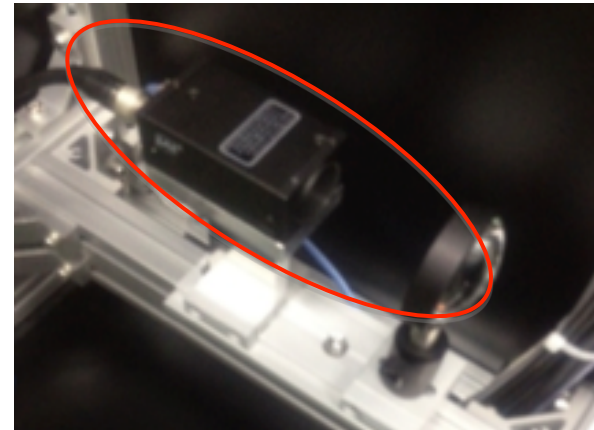
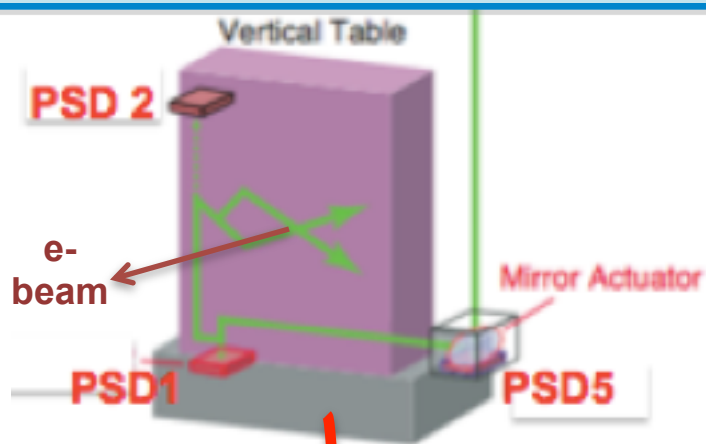
Schedule:

assembling of new setup completed

❖ Now (Sep, 2012): **Beam off tests** prepare for autumn run (10/15~)

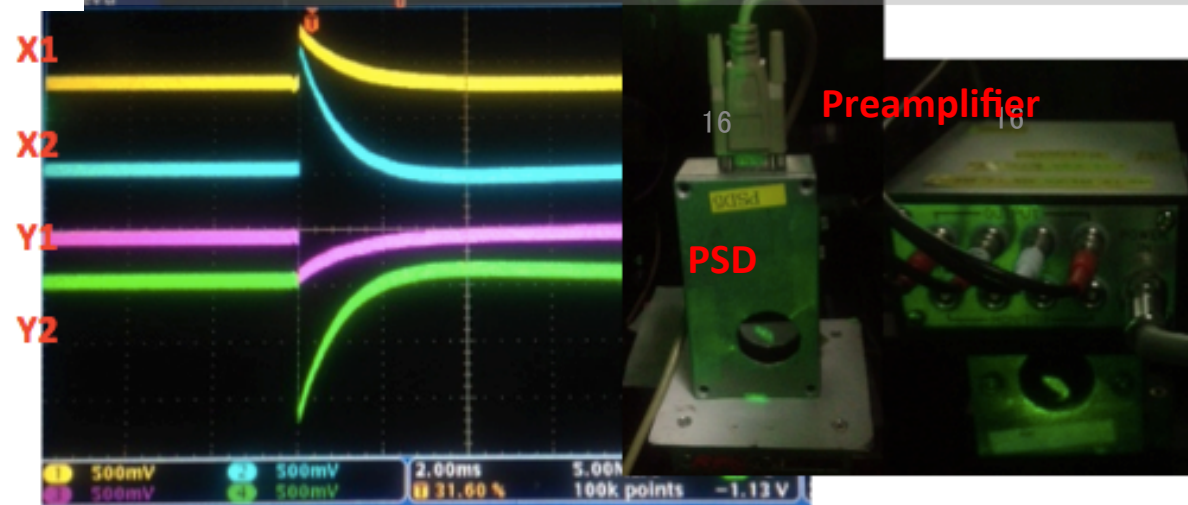
Hardware (re)commissioning PSDs, phase monitor, profile monitors, DAQ modules, ect....

Tests of PSDs (+ preamps, readout circuit)



CCD camera
as
profile monitor

Signal output from PSD electrodes



SUMMARY

IPBSM (“Shintake Monitor”) installed at ATF2 IP

- use **laser interference fringes**
→ **only device capable of measuring $\sigma y^* < 100$ nm**
- Crucial for beam tuning → realization of future linear colliders

< Status >

- ❖ **Stable measurements of $\sigma y^* \sim 160$ nm (30° mode)**
- ❖ dedicated systematic error study (2 – 8 °mode)

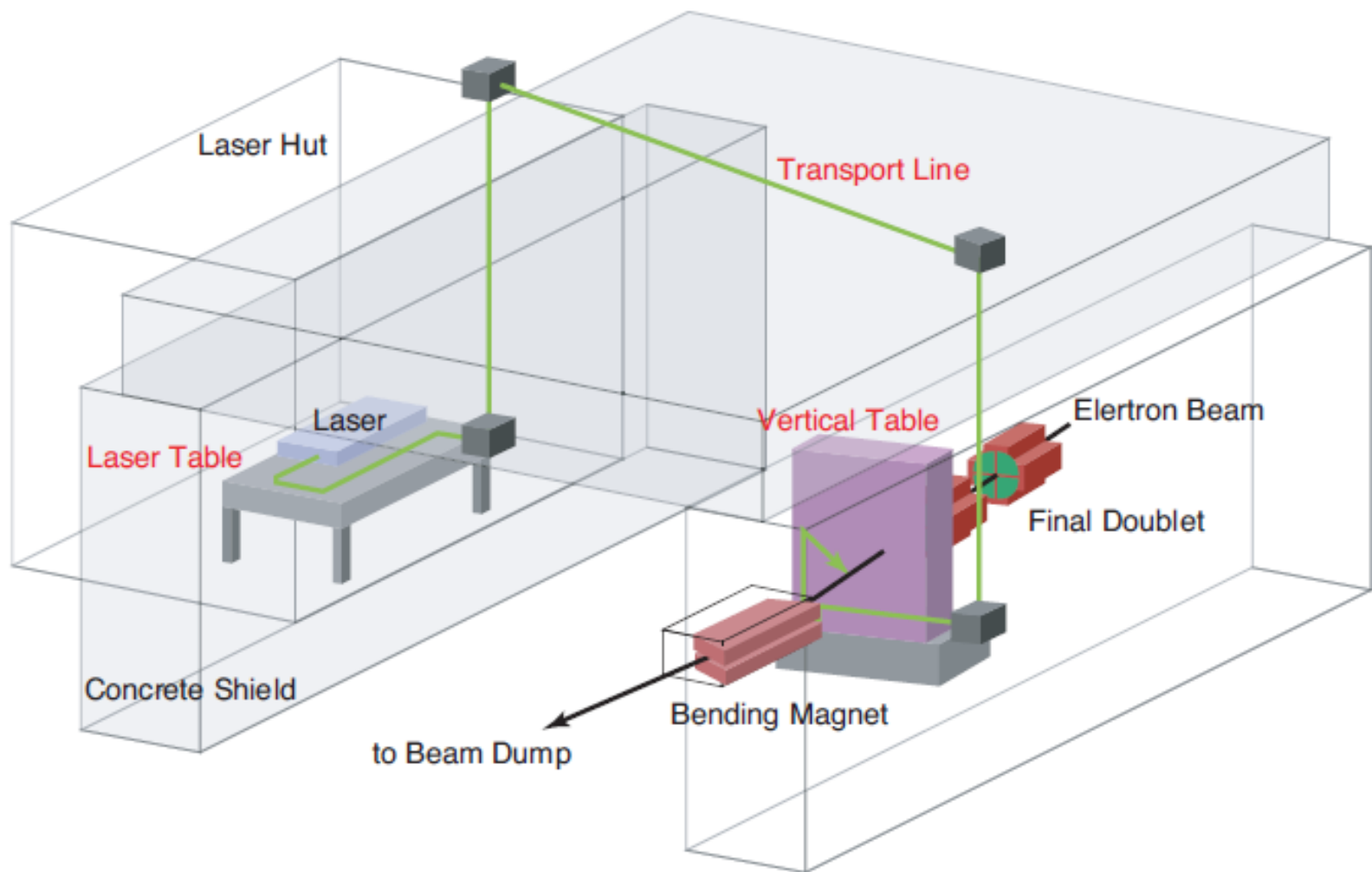
<upgrades>

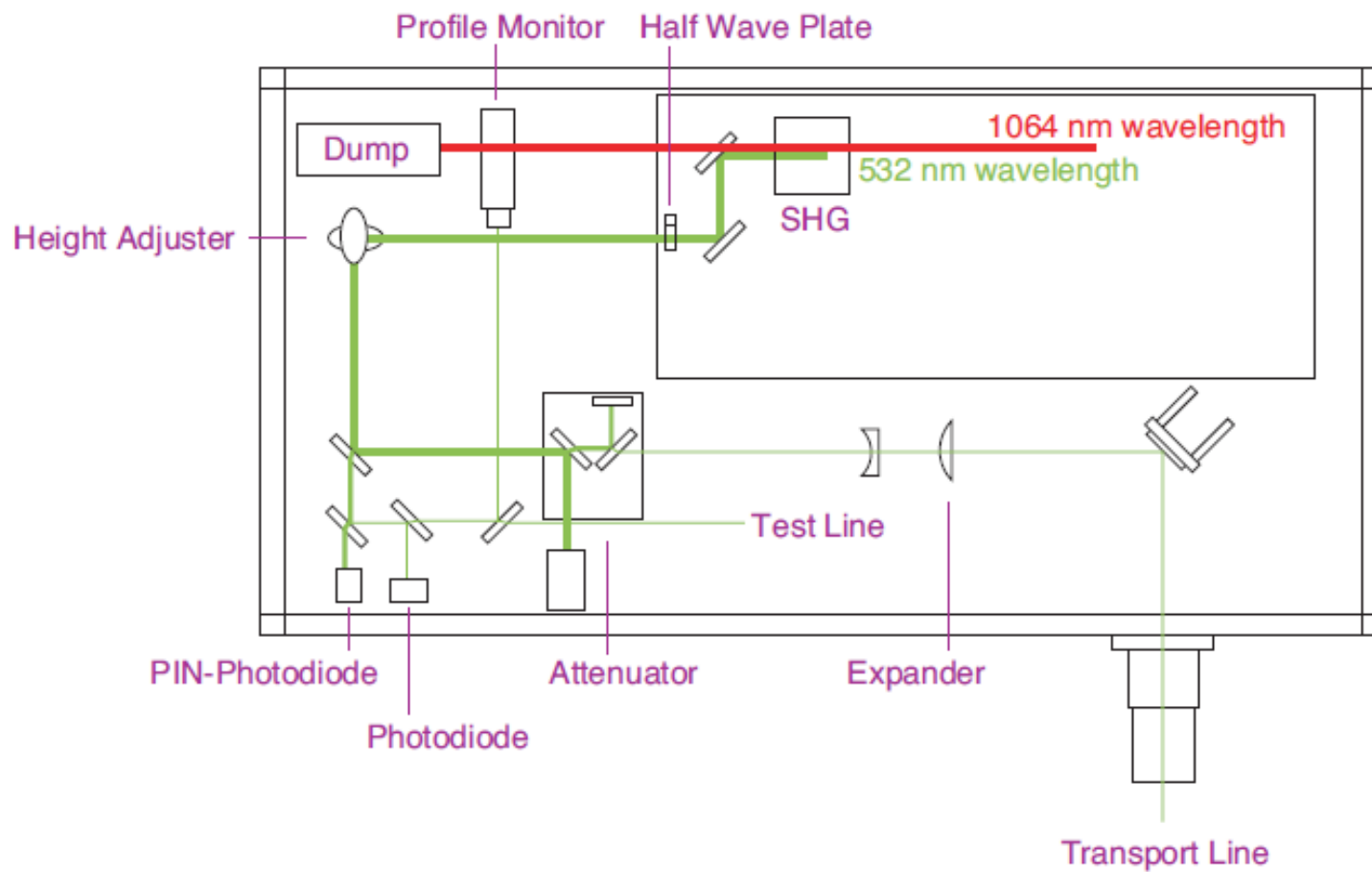
- suppress jitters & bias factors
- stabilize laser system
- **reliability & reproducibility in laser optics alignment**

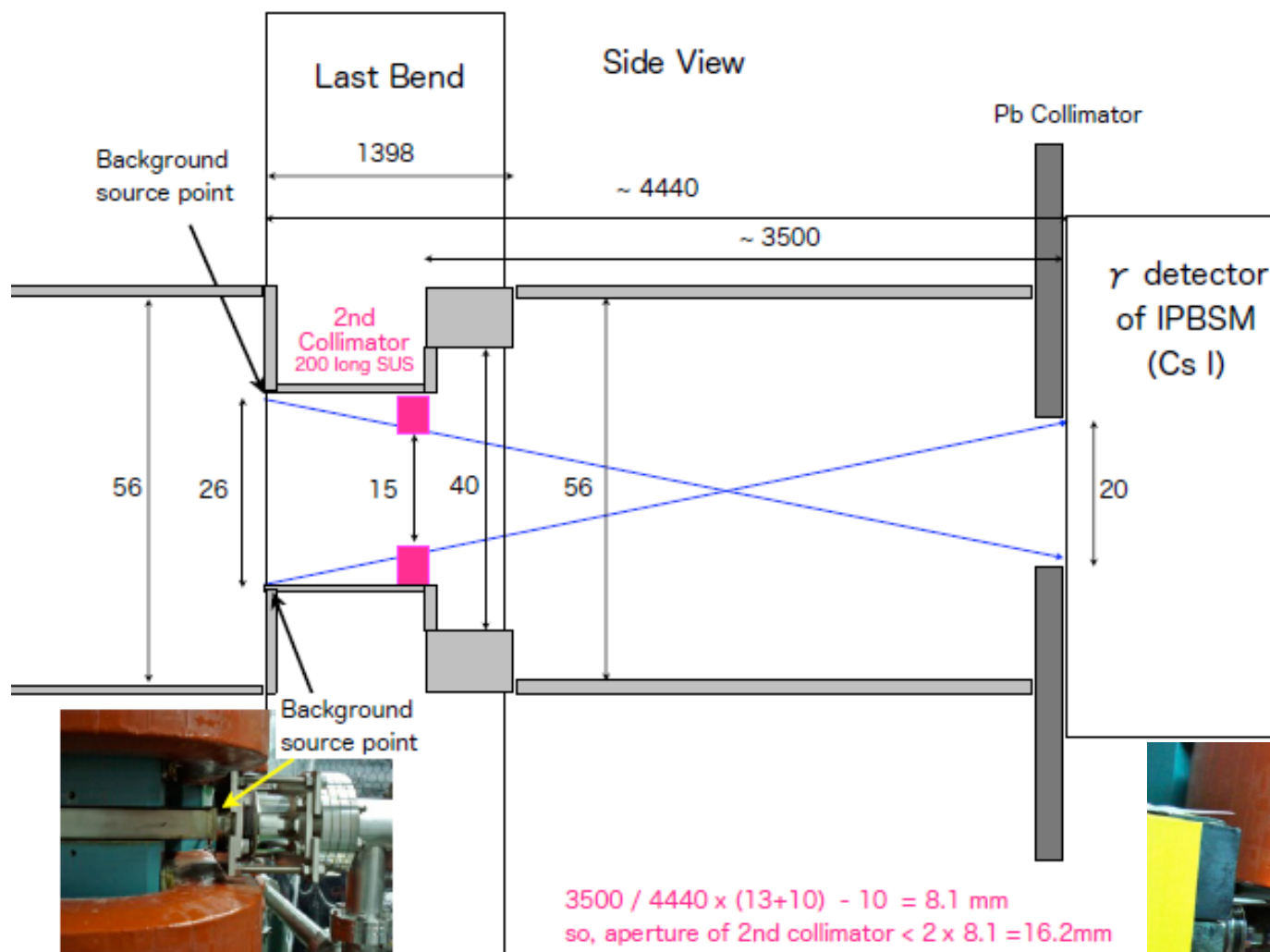
< Goals for 2012 autumn beam run >

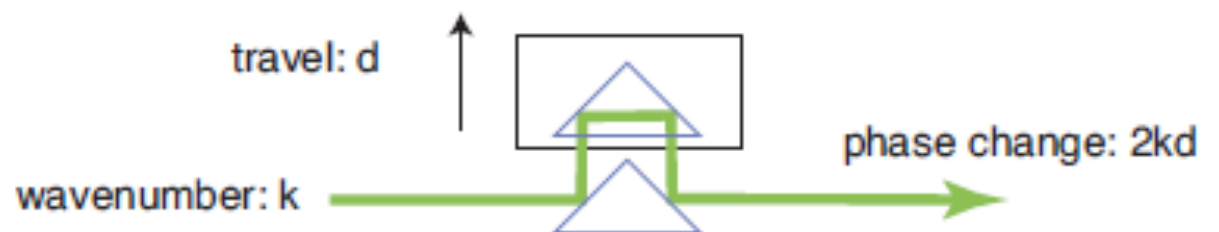
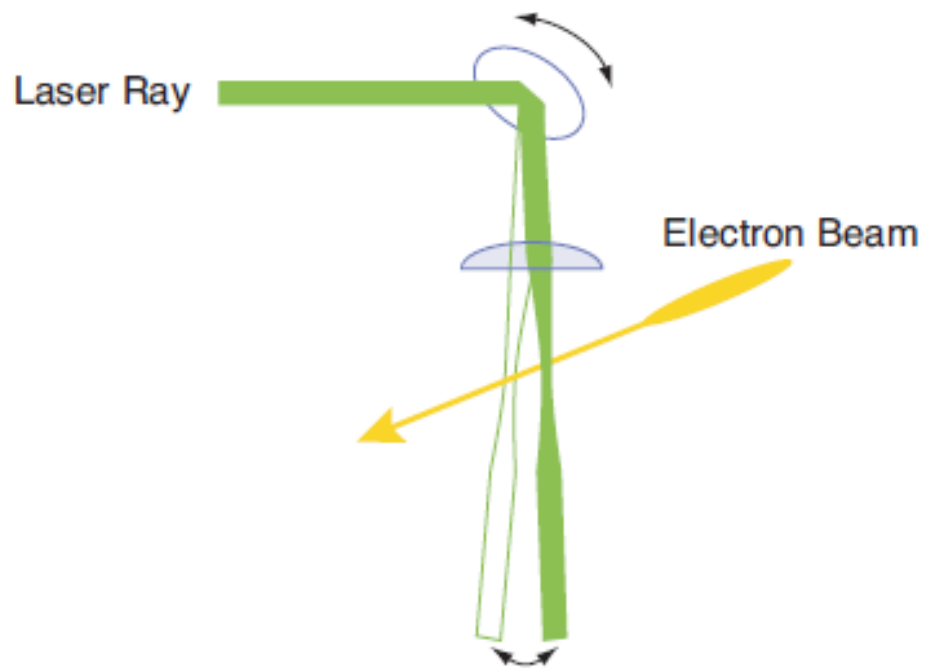
- ◆ full commissioning of 174 ° mode
- ◆ stable measurement of $\sigma y^* < 100$ nm
→ achieve focusing down to $\sigma y^* \sim 37$ nm

BACKUP

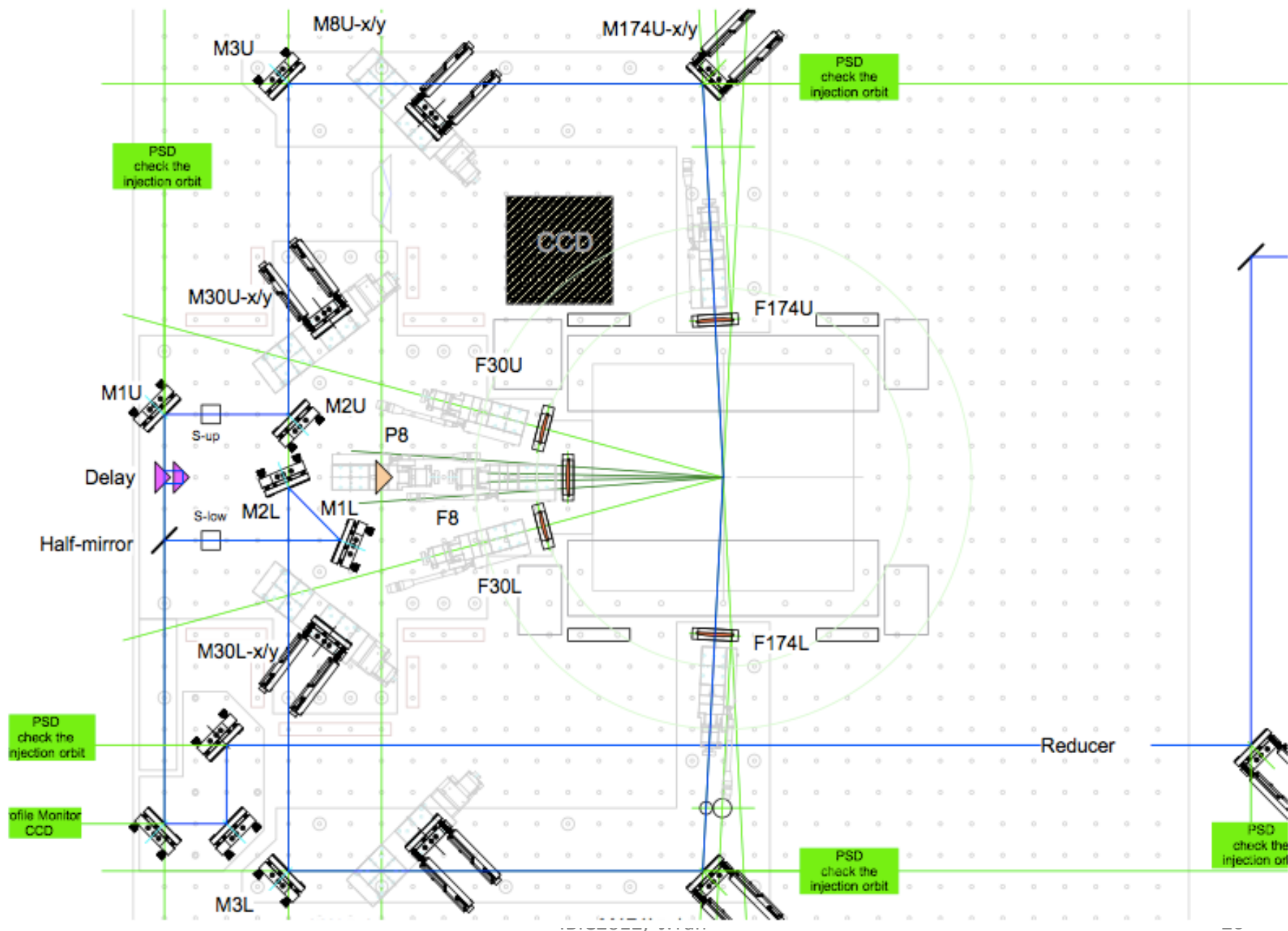








New 174 mode



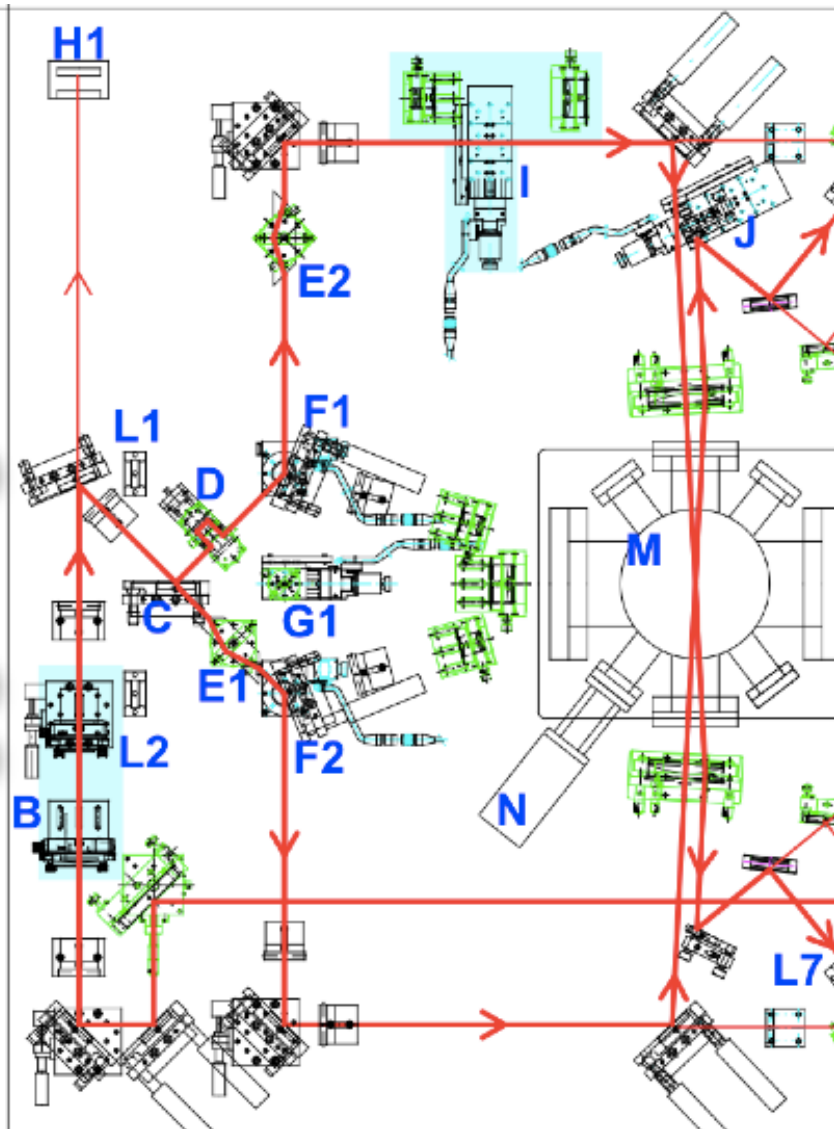
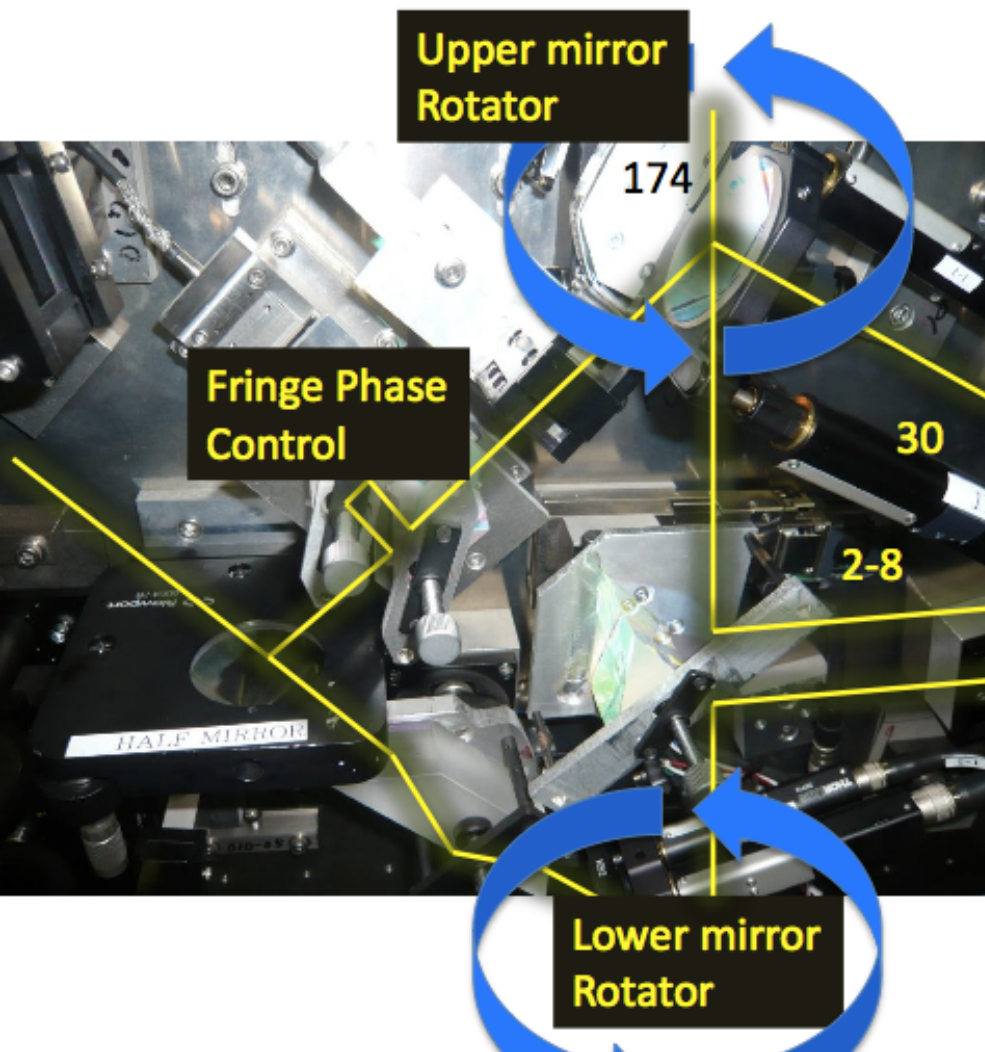


Table 3: Upper limits of each M reduction factor predicted for measuring the design $\sigma_y^* = 37$ nm at ATF2. Assumed here are nominal laser and ATF2 beam parameters, as well as implementation of specific correction functions for the sensitive 174 deg mode used in this case[6].

Modulation reduction factor	37 nm at 174 deg
Total power imbalance	> 99.8 %
Relative position jitter	> 98.0 %
Fringe tilt	> 97.2% (tilt < 1 mrad)
Alignment (t, z)	(> 99.6%, > 99.1 %)
Spatial coherence	> 99.9%
Spherical wavefronts	> 99.7%
Beam size growth within fringe	> 99.7%

Table 4: Upper limits of dominant M reduction factors for measuring $\sigma_y^* \sim 500$ nm at 4 deg mode, estimated using data from June, 2012

Modulation reduction factor	O(500) nm at 4 deg
Profile imbalance (t, z)	(> 94%, > 89 %)
Relative position jitter	> 95 %
fringe tilt (t, z)	> 95% (tilt < 20 mrad)
Alignment (t, z)	(> 95%, > 99 %)
Polarization	> 98%

laser path misalignment

1 . Laser profile imbalance

misalignment of final lens focal point
divergence angle affected by reducer setup

In past:

replaced damaged optical components

optimized lens / reducer setup, alignment methods

2. Laser position offset from IP (beam center)

→ not a concern,
mirror actuators finely adjust
to $1/10$ of σ_{laser}

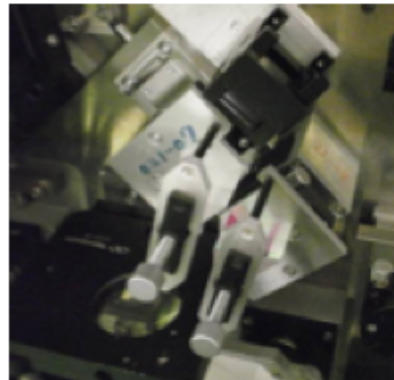
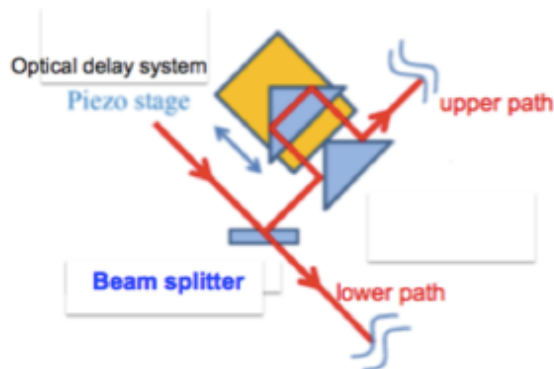
long. : Cz- pos > 99.5 %

transv : Ct-pos ~ 100%

Polarization related errors

→ imbalance in intensity/ profile

→ half mirror R = 50% only for pure S state
elliptical components (P contamination)



adjust to S state
by rotating $\lambda/2$ wave plate

•measured in past :
half mirror properties,
eccentricity $E_s : E_p = 1 : 0.13$

→ $C_{\text{pol}} = 97.8 \pm 12.8 \cdot \tan\theta \pm 0.1\%$
(2-8, 30 deg)

$C_{\text{pol}} = 97.2 \pm 1.3 \cdot \tan\theta \pm 0.1\%$
(174 deg)

for now assume **Cpol ~ 98 %**

Figure 4.7: [Left] The optical delay system for controlling fringe phase. [right] The piezoelectric stage

顕著な系統誤差 (2012連続ランより)

夏の光学系アップグレードで系統誤差を改善

Profile Imbalance

- ✓ Compton peak power の違い: $C_{pow} \sim 98\%$
- ✓ IP spot size σ_{laser} の違い: $C_{pro} \sim 90 - 95\%$

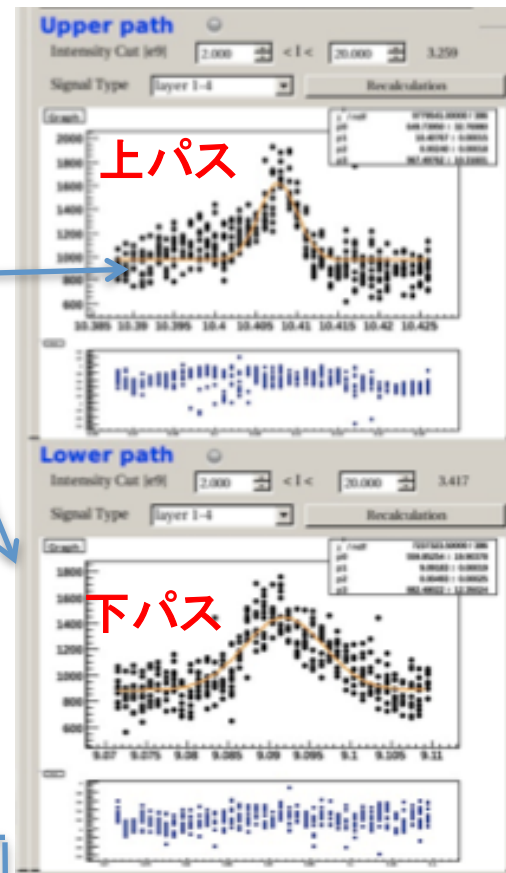
◆一部は光学素子由来のロス
(反射・透過率、光路長差ect...)
total $P_l = 0.88 \leftrightarrow C = 99.8\%$

◆lensのalignment精度
(→ 焦点位置のばらつき)

$$M' = CM = \frac{2\sqrt{P_l}}{1 + P_l} M$$

$$P_l \equiv P_U / P_D$$

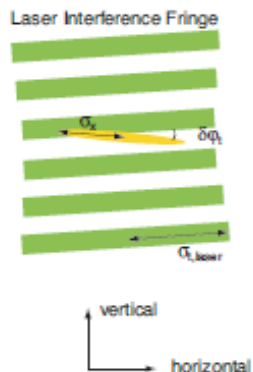
実laserwire
scan



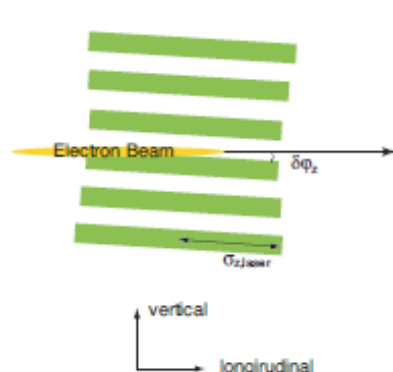
上図) 2倍の信号量の差

Fringe Tilt

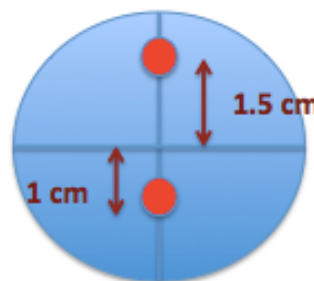
干渉縞がbeam軸に垂直でない場合



transverse



longitudinal

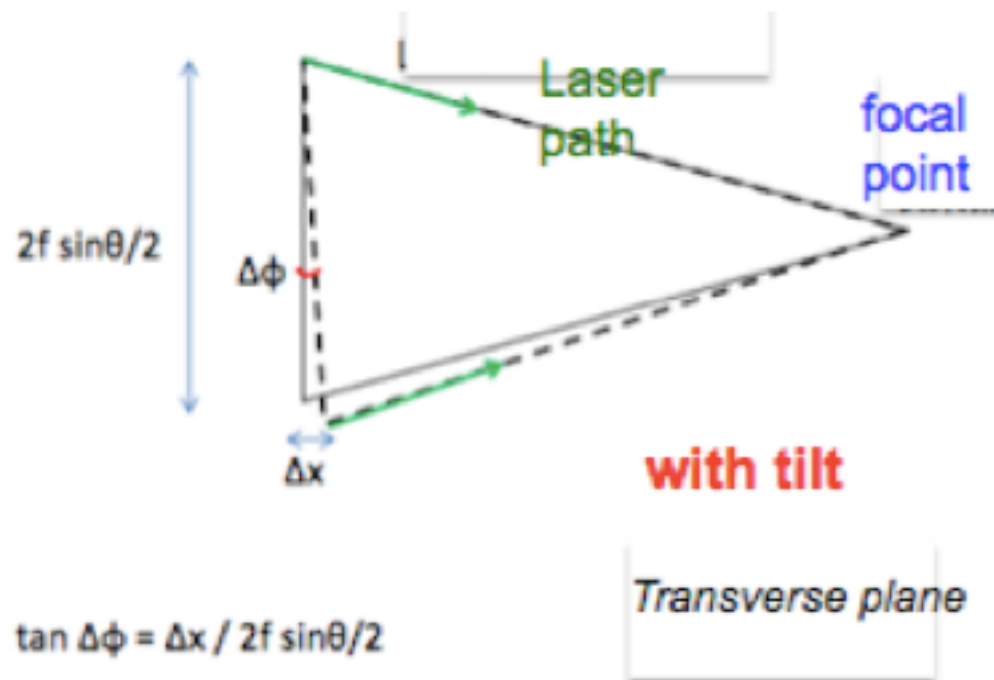
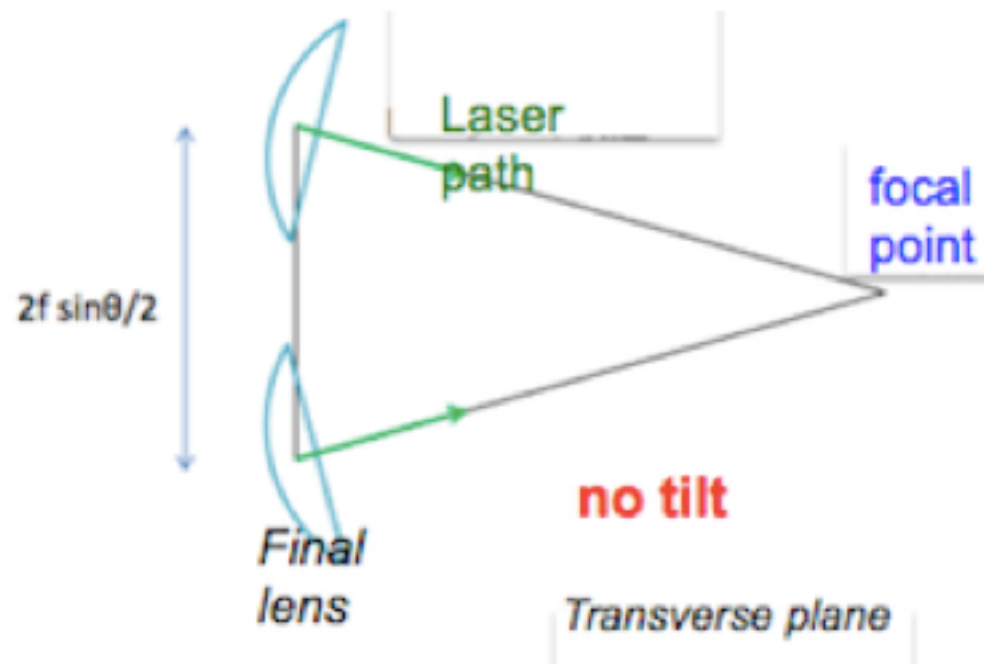


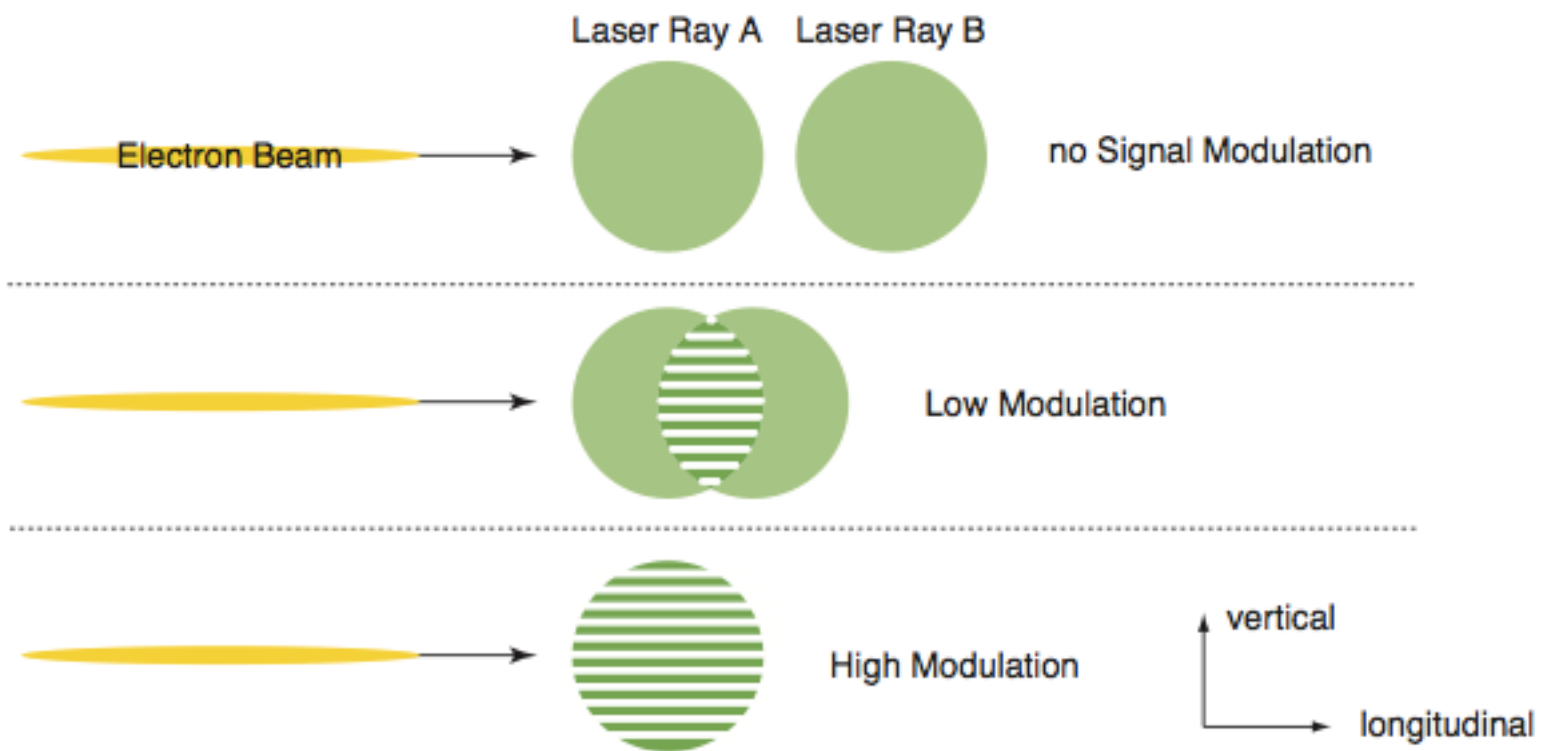
見積もり方:
収束レンズ中心からの
相対的オフセット $\Delta t, z$

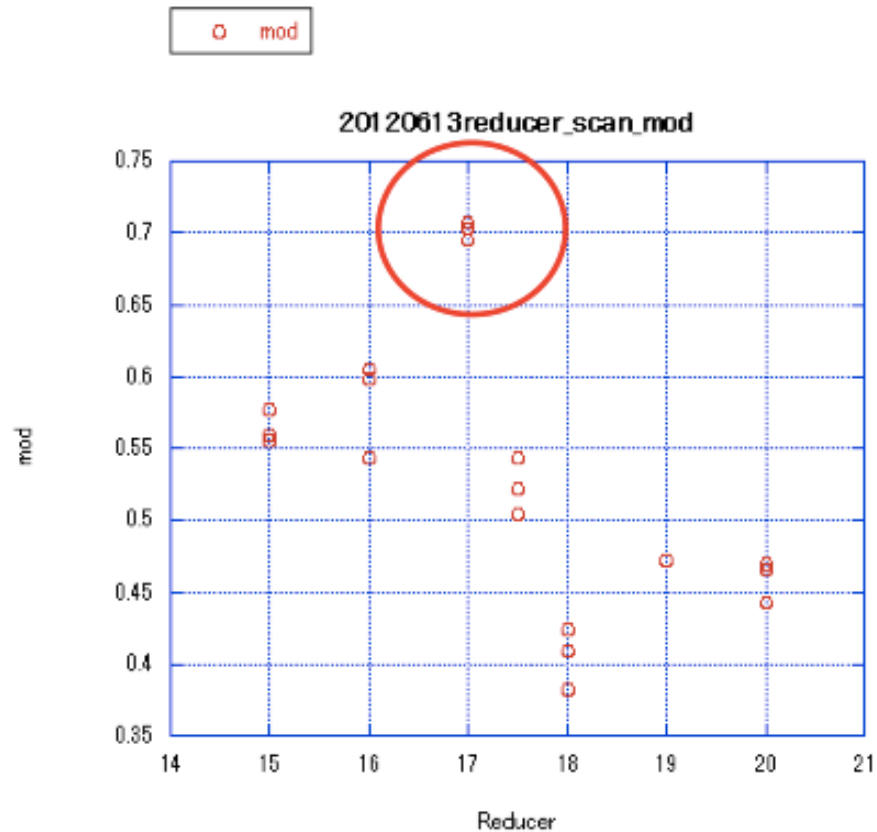
光路精度 $\Delta < 3 \text{ mm}$

→ 傾き: $\delta\phi_t < 10 \text{ mrad}$
 $\delta\phi_z < 5 \text{ mrad}$

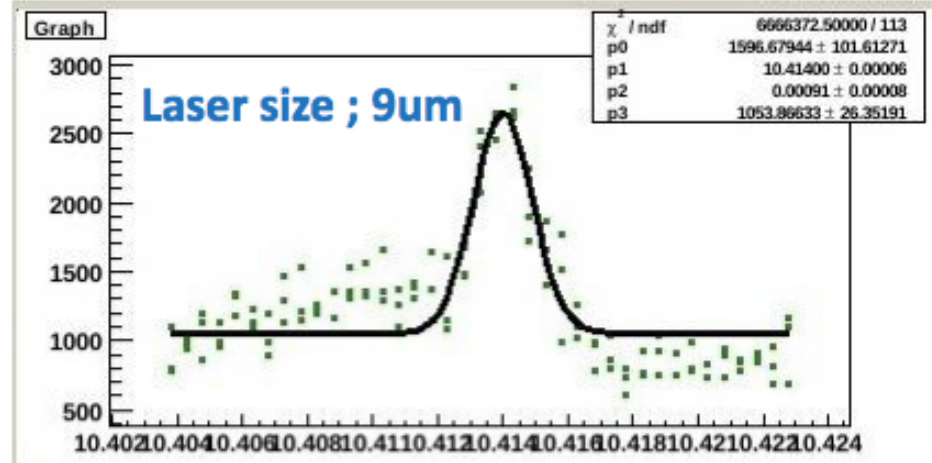
Ct-tilt > 95.3%
Cz-tilt > 99.8%



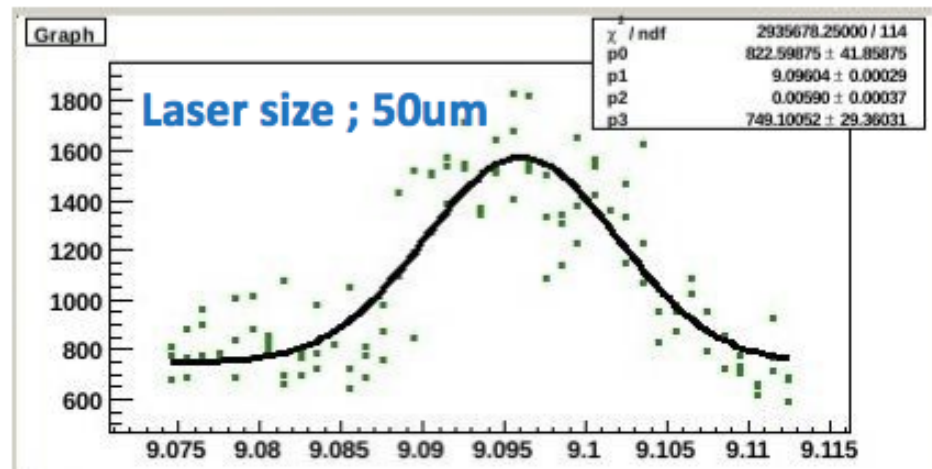




Very narrow optimum setting



Beam profile of lower path



Current status of laser system

relative timing	Stabilized by timing scans TDC, TD2 modules
Intensity	• Stability ~ 1% • optics damaged by high intensity laser in March • Safe at ~ 40% power for now
Oscillation	currently stable •exchanged flash lamps and seeder • cavity mirror tuning
profile	Triangular (non-Gaussian) profile at IP dark spots → Improved by rear mirror tuning
Major upgrades in laser optics	• Beamlok • new laser table box • additional mirror for precise injection onto vertical table • changed reducer and expander lens (AR coating , magnification)



Stat errors

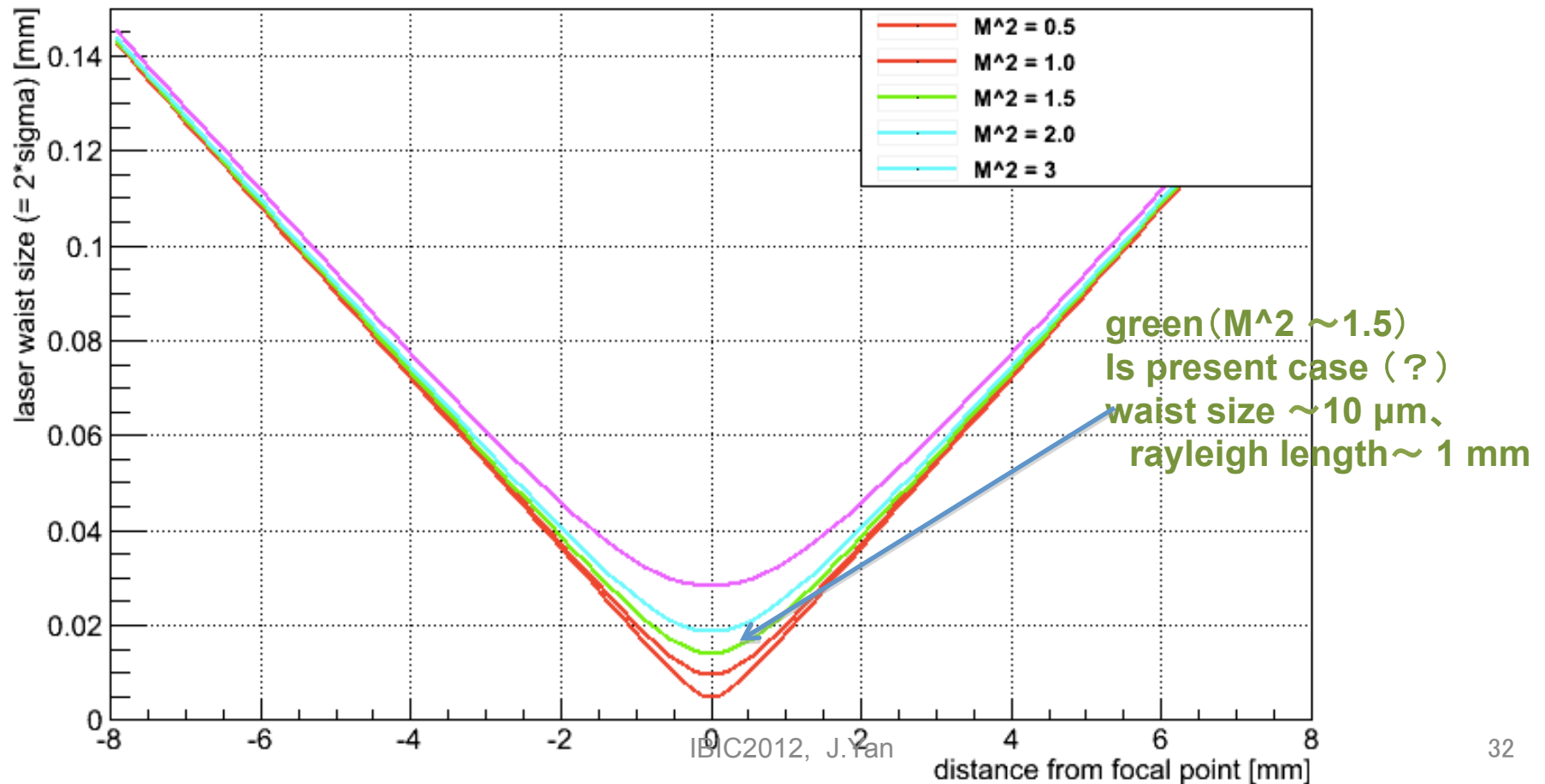
Laser timing	1 - 3 %
Laser intensity	1.5%
Beam intensity jitters	ICT monitor resolution: 2-5% (Measured energy is normalized by ICT)
Laser pointing stability	10 ~ 15%
Beam position jitters	unknown

M^2 : 0.5 – 3.0

near field to few times of rayleigh length

- Assume injected size of $\omega = 4.5$ mm,
- fix focal point to 5.6 mm (lens mover position)

beam focusing dependence on M^2



4 consistent measurements at 4 deg mode :

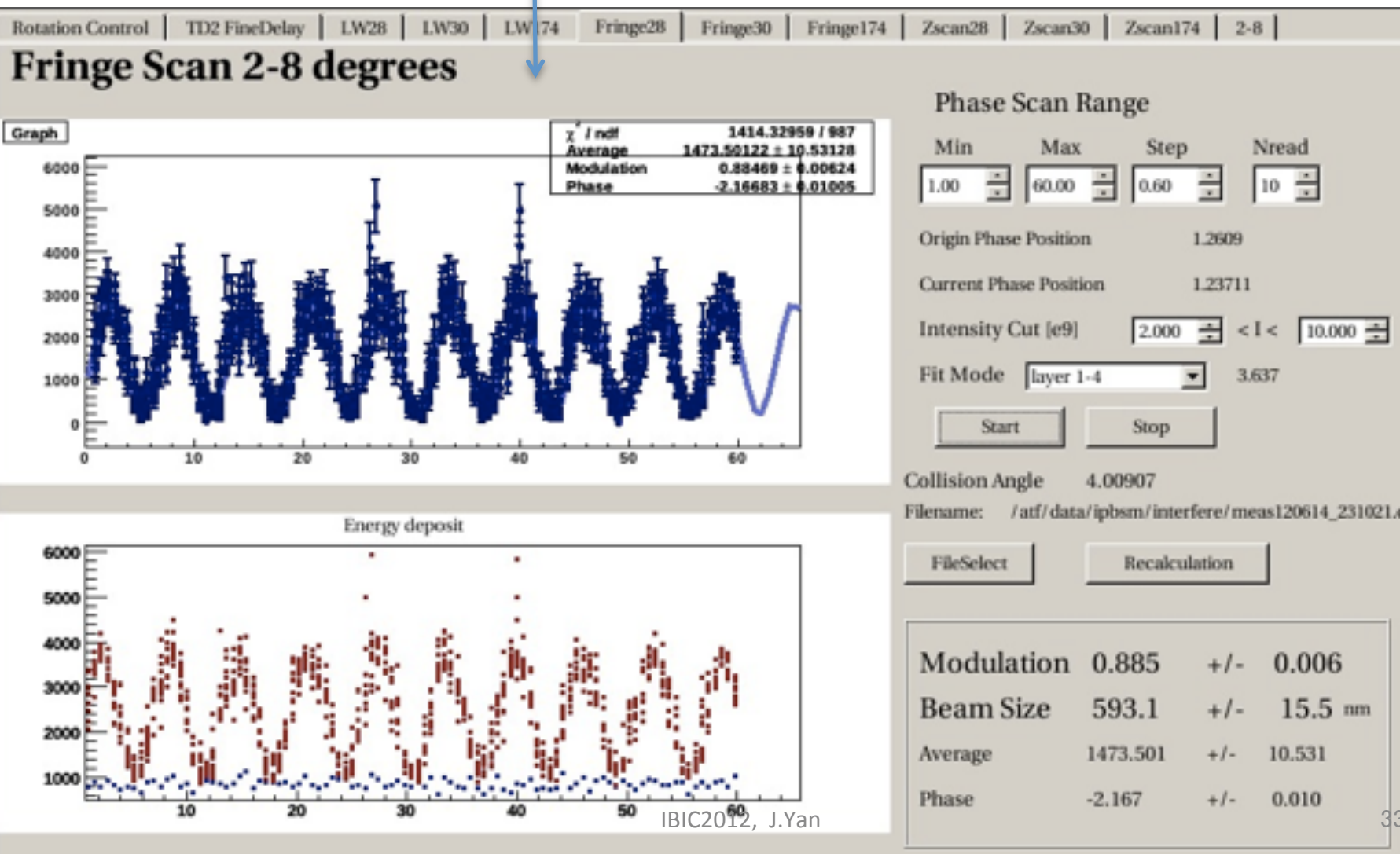
including long range fine scan (60 rad, Nav = 10)

$M = 0.887 \pm 0.005$ (stat only)

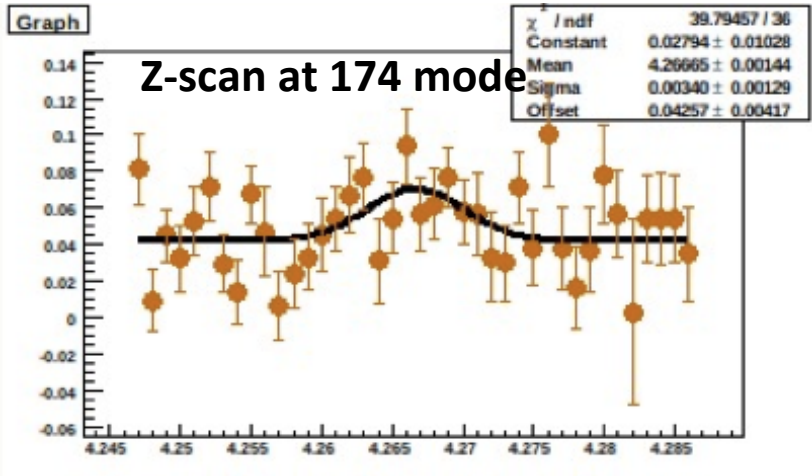
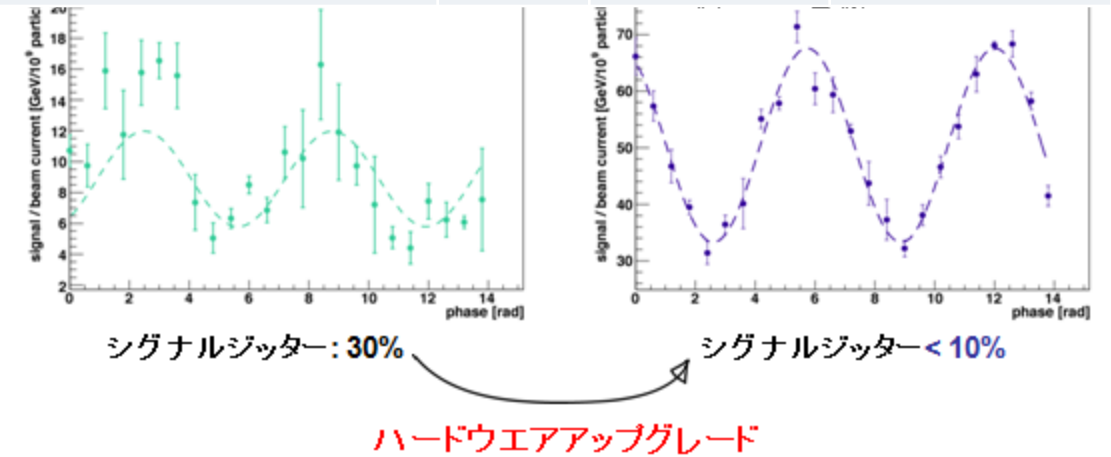
$\sigma_y = 589 \pm 13$ nm

init. phase: -2.162 ± 0.009 rad

phase drift ~ 18 mrad (~ 0.8 % only)

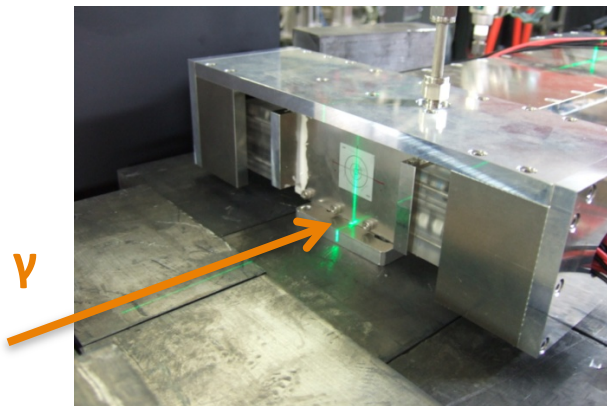


optics for recent run	S/N	BG [GeV]	Sig. jitter
10x βy^* (ex: 30 deg)	4	5	15 – 25%
3 x βy^* (ex: 2- 8 deg)	1	15	
1 x βy^* (ex: 174 deg)	0.5	20	
		BG のふらつき ~10 – 15 %	



ガンマ線検出器

カロリメータ型CsI(Tl)シンチレータ

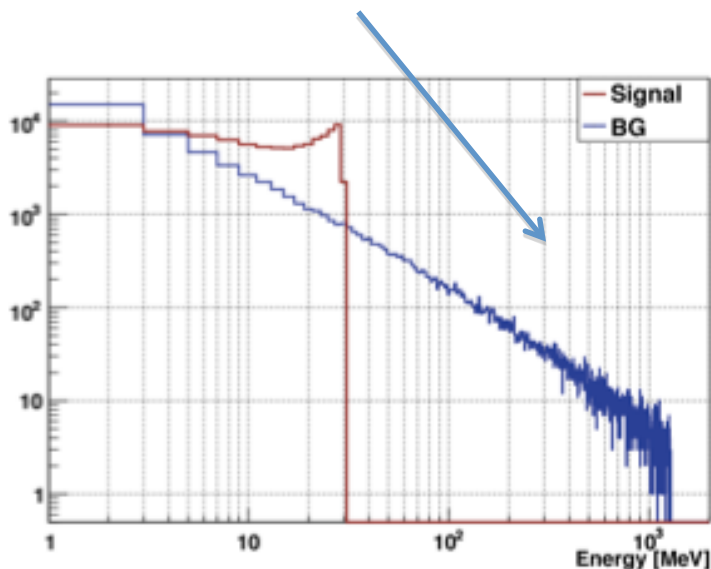


多層構造

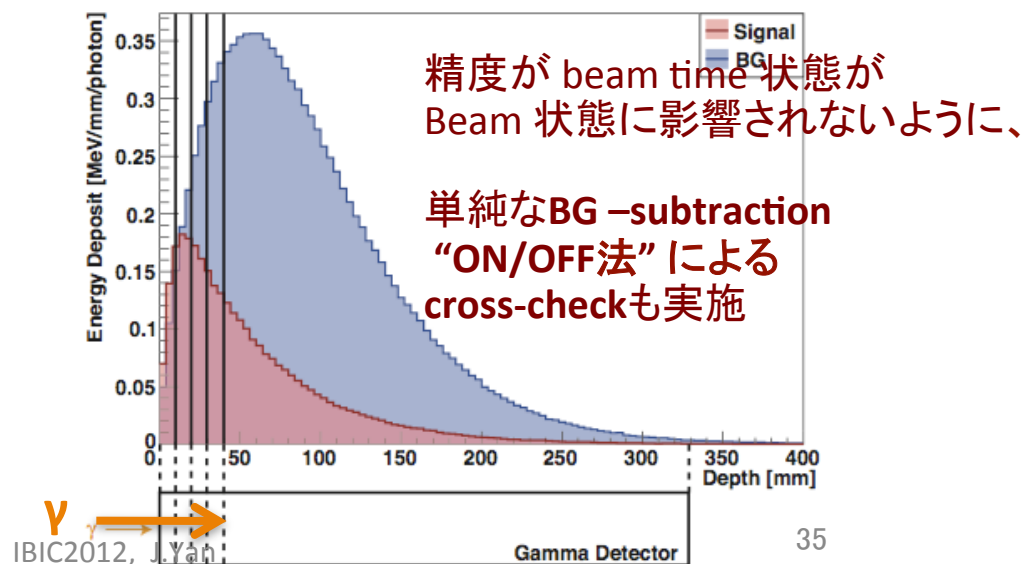
前4層 (10 mm x 4) + 後ろの "bulk" (290 mm)

高いシグナル・BG分離能

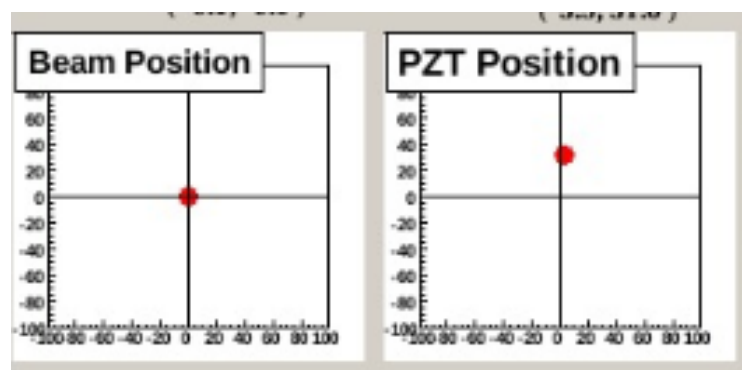
ATF2 でsignalとBGエネルギースペクトルが大きく違うことを活用



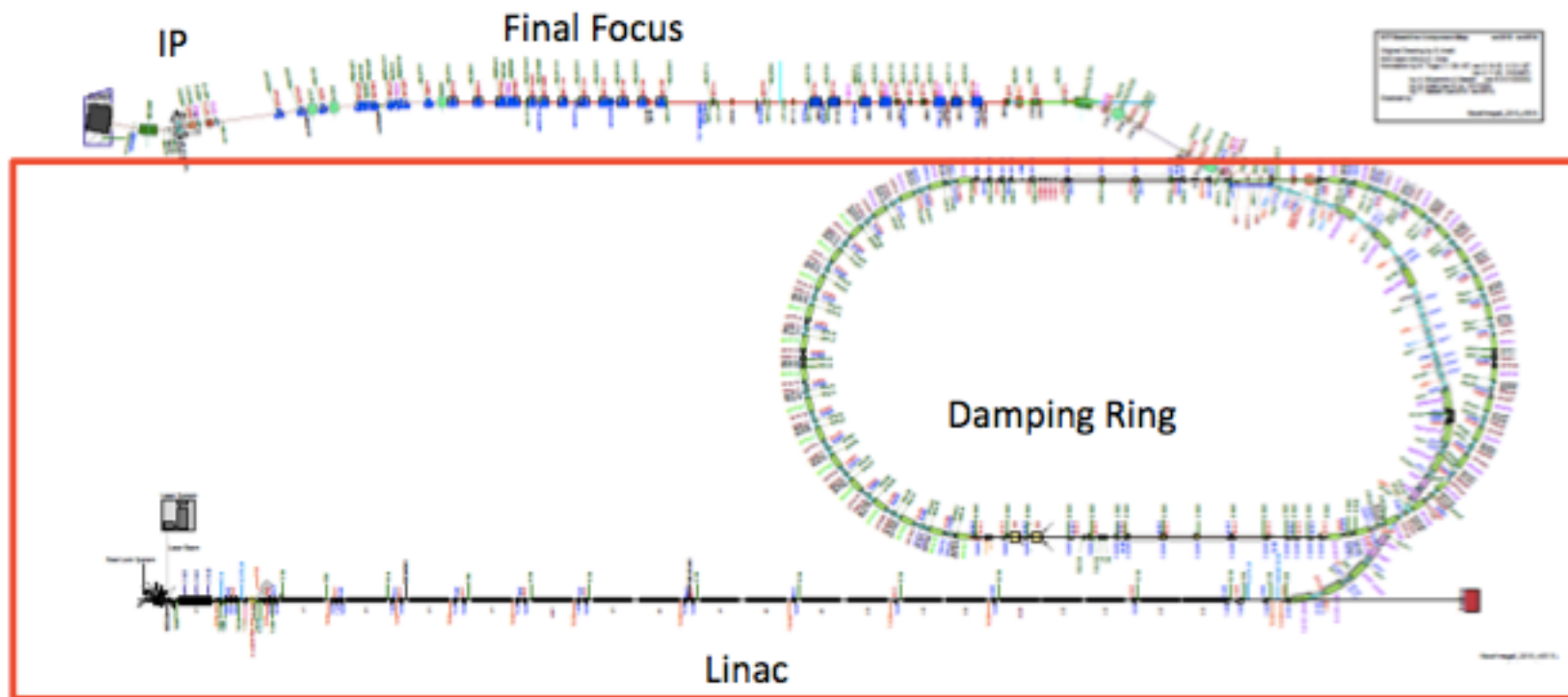
各層でのシャワー発展を測定
→参照シャワーでfitting



BeamLok Specifications		Standard Pro Series	With BeamLok/D-Lok
Beam Pointing Stability ¹²		$<\pm 50 \mu\text{rad}$	$<\pm 25 \mu\text{rad}$
Beam Divergence ¹³		$<0.5 \text{ mrad}$	$<2 \times \text{initial level}$
Lamp Lifetimes ¹⁴		30 million pulses	40 million pulses
Linewidth			
	Standard	$<1.0 \text{ cm}^{-1}$	
	Injection Seeded ¹⁵	$<0.003 \text{ cm}^{-1}$	
Timing Jitter ¹⁶		$<0.5 \text{ ns}$	



ATF



Linac: ビームエネルギー1.3 GeV

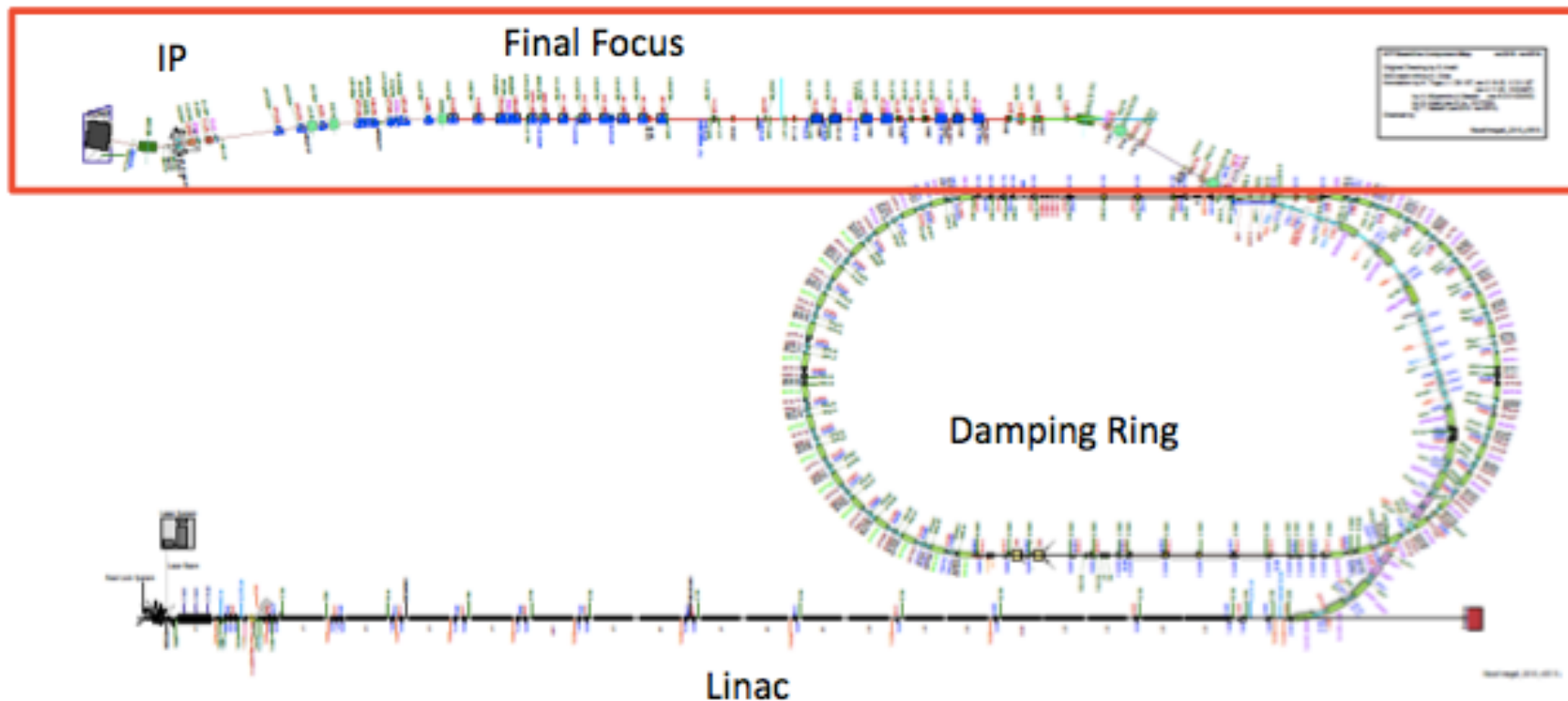
Damping Ring: 鉛直エミッタンス11 pm·rad



規格化鉛直エミッタンス30 nm·rad

ILCでの規格化エミッタンス35 nm·rad

ATF2



Final Focus: 局所色収差補正に基づいた設計

- 37 nmの鉛直ビームサイズ → 新竹モニタで測定
- nmレベルのビーム安定化 100 nm以下のビームサイズ測定に実績

FFTB vs ATF2



Table 2: Typical e- beam and IPBSM parameters: ATF2 vs FFTB[2, 4]

	FFTB	ATF2
Beam energy	46.6 GeV	1.28 GeV
1 photon energy	8.6 GeV	15 MeV
rep. rate	30 Hz	1.56 Hz (3 Hz)
e- / bunch	1×10^{10}	1×10^{10}
Bunch length	3 ps	16 ps
(σ_x^*, σ_y^*) at IP	(900, 60) nm	(2200, 37) nm
Laser wavelength	1064 nm	532 nm (SHG)
Range for σ_y^*	40-720 nm	20 nm-6 μ m

